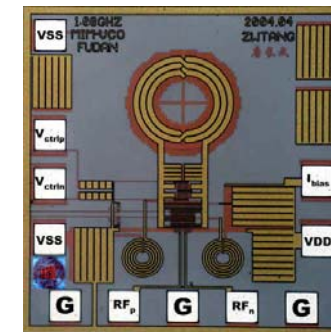




CMOS射频集成电路设计

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片上螺旋电感

- 简介
- 射频集成电路中的电感
- 片上螺旋电感
- 平面螺旋电感的分析和建模
- 等效电容的计算
- 提高品质因数的几种方法
- 片上电感的在片测试
- 中心抽头差分电感的等效模型和参数提取

简介

- 射频集成电路的市场潜力
 - 无线收发机: **WLAN, Bluetooth, WCDMA, TD-SCDMA**
 - 宽带调谐器: **Mobile Tuner, DVB-T TV Tuner**
- **CMOS技术的发展**
 - 工作频率<**10GHz**, 截止频率**30-50GHz**
 - 比**GaAs, SiGe, Bipolar**工艺便宜
 - 高集成, 高性能
 - ❖ 数字和模拟
 - ❖ 有源和无源器件: **MOS**, 二极管, 电阻, 电容, 电感
- 设计电感能否像**MOS管**一样方便?
 - 建模是难点
 - 品质因数**Q**的优化和自激振荡频率 f_{RS} 的优化

片上电感的三种类型

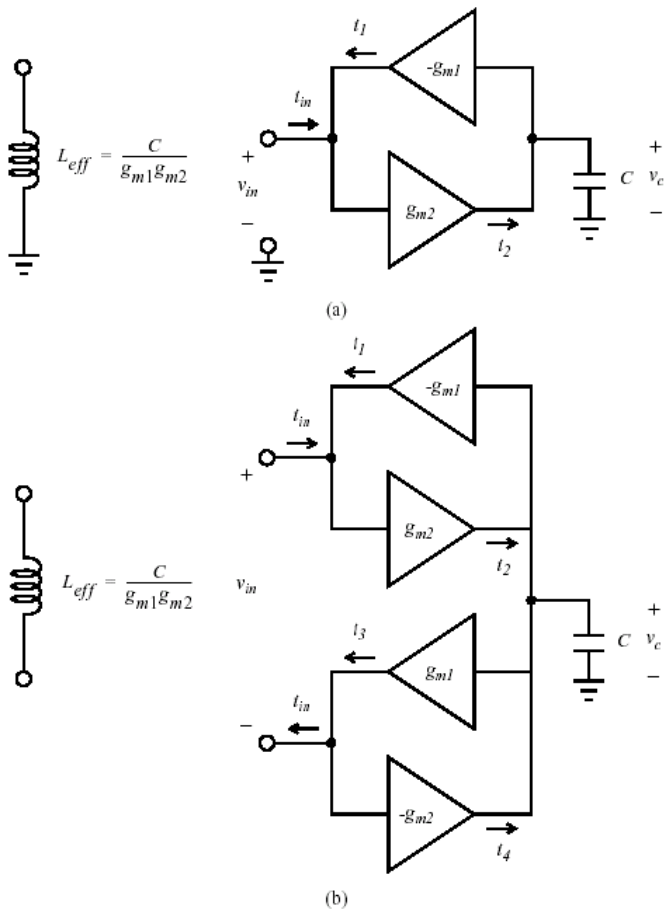


图1 有源电感

(a) 单端结构, (b) 双端结构

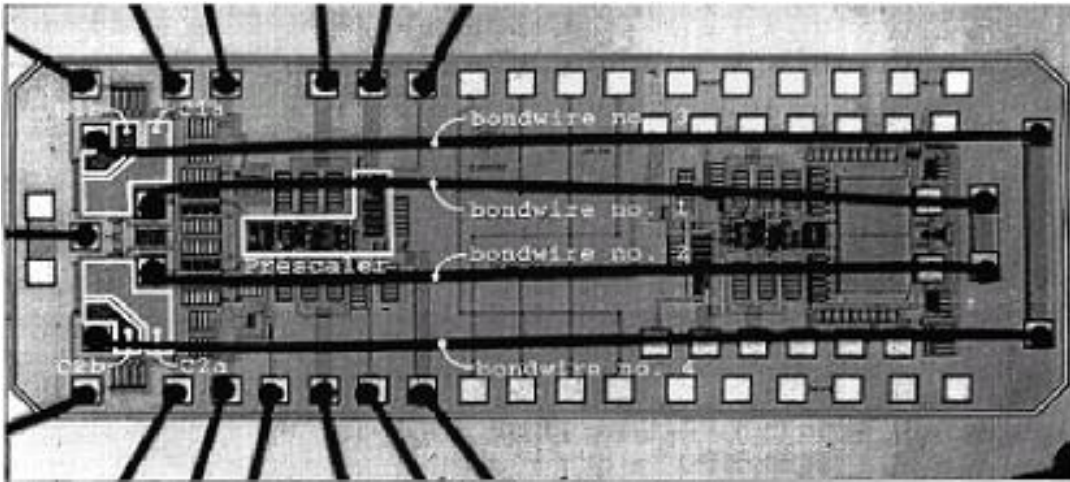


图2 键合线电感

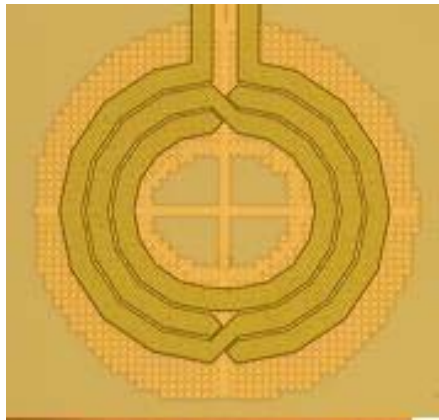
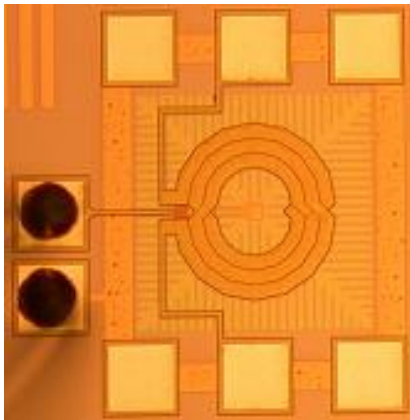


图3 片上螺旋电感

射频集成电路中的电感(I)

● 射频集成电路

□ 低噪声放大器, 混频器, 压控振荡器, 功率放大器, 高频带通滤波器和阻抗匹配网络

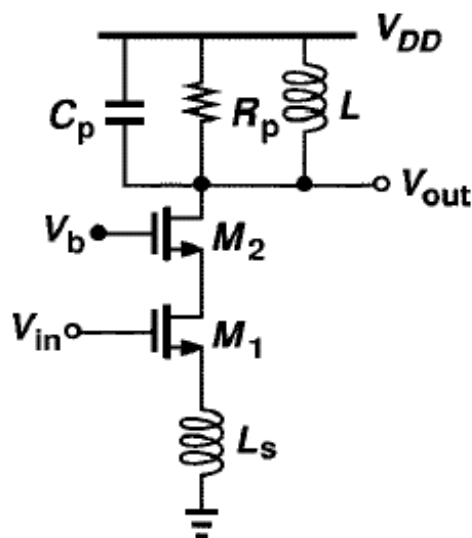


图1 低噪声放大器

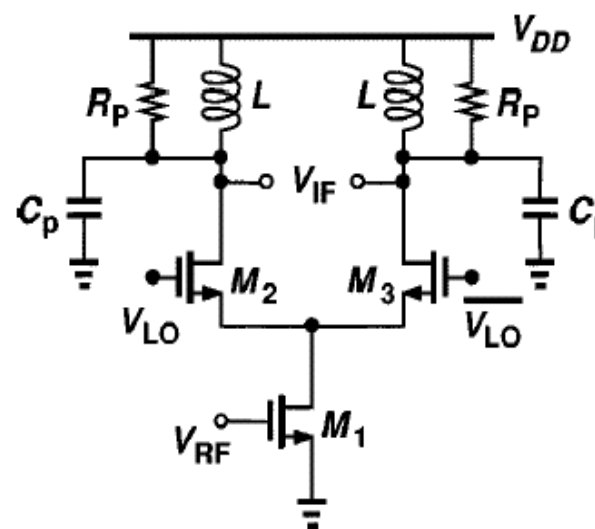
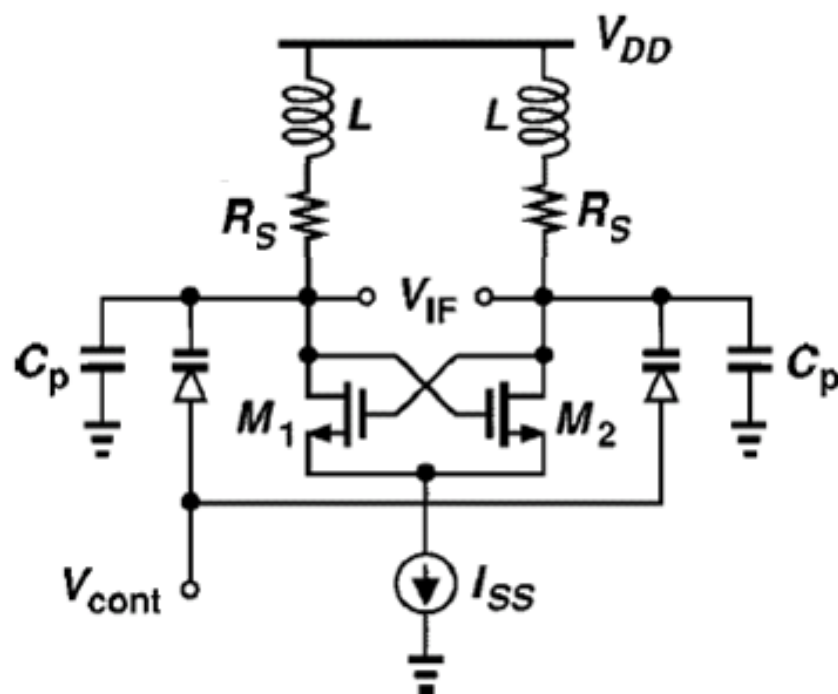


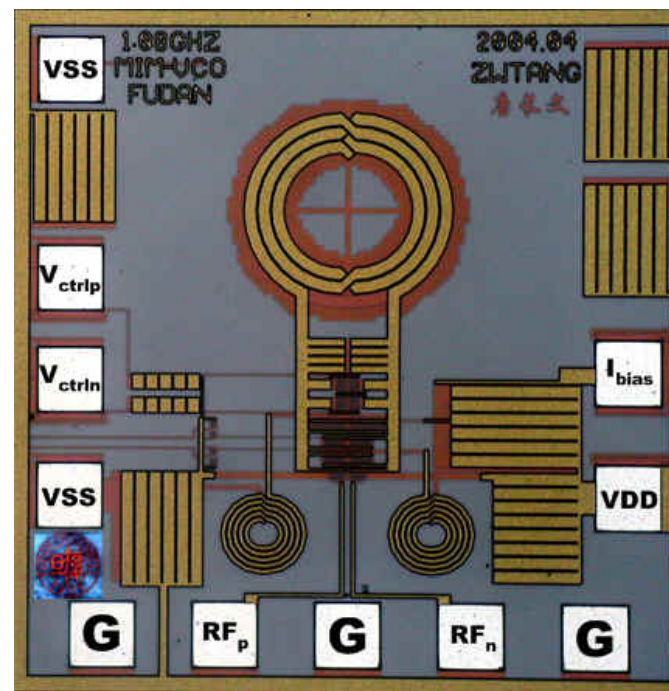
图2 频混频器

为了提高增益(转换增益), 增大片上电感的等效并联电阻。



压控振荡器电路与版图照片

- 为了提高品质因数，降低片上电感的串联电阻。
- 为了提高压控振荡器的调谐范围，减小并联电容。



唐长文

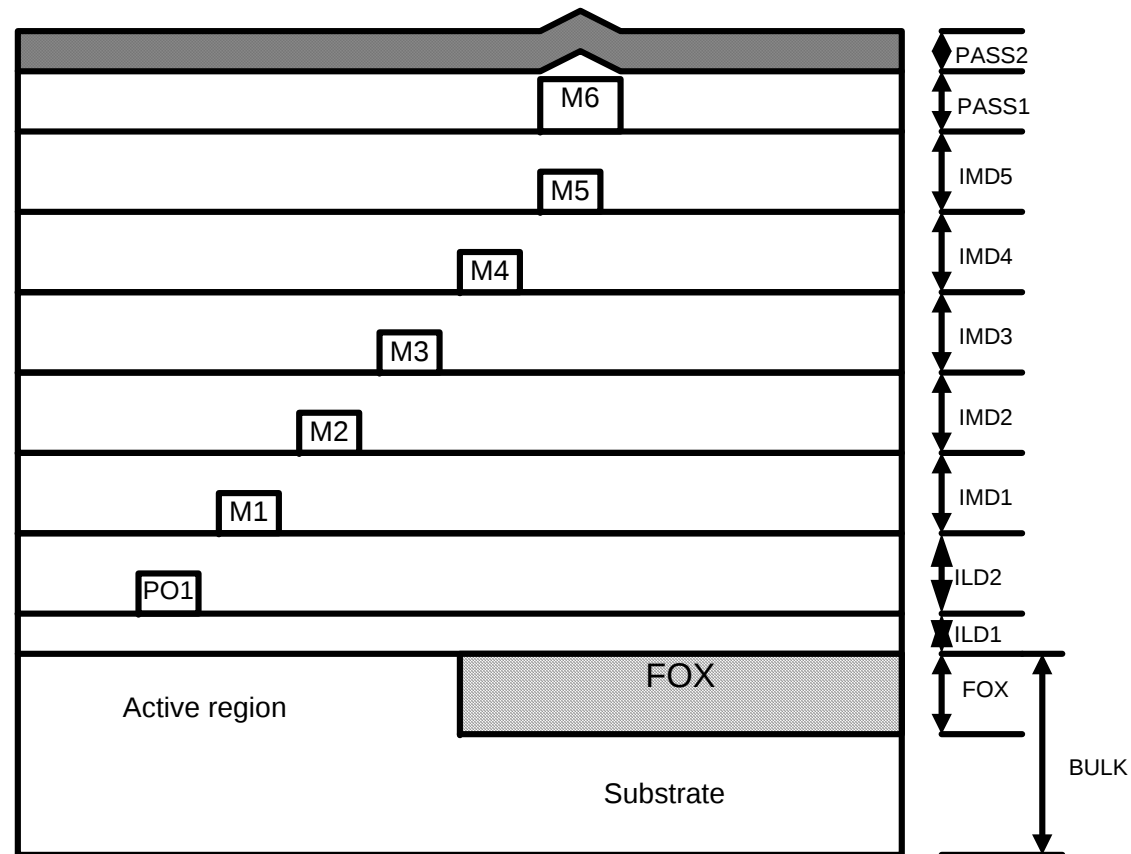
射频集成电路中的电感(II)

● 片上电感的功能和作用

电路	功能	作用
低噪声放大器	输入阻抗匹配 源极退化 谐振负载	同时满足功率和噪声的匹配 提高线性度 线性度最佳偏置, 滤波, 消除寄生电容的影响
混频器	源极退化	增加线性度, 减小噪声
振荡器	谐振	确定振荡频率, 高品质因数电路 降低功耗, 减小相位噪声
功率放大器	功率匹配 谐振负载	增大电压摆幅, 提高功率效率

片上螺旋电感

● CMOS工艺互连线



CMOS工艺互连线剖面图

平面螺旋电感(I)

● 横向参数

□ 圈数, n

□ 金属宽度, w

□ 金属间距, s

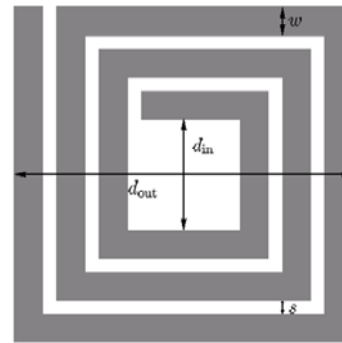
□ 外直径, d_{out}

内直径, d_{in}

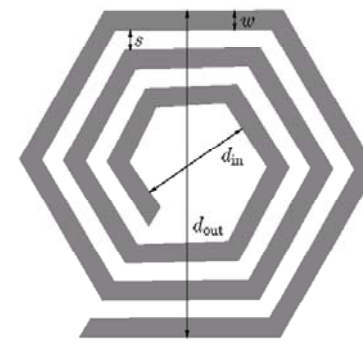
填充率,

$$\rho = (d_{out} - d_{in}) / (d_{out} + d_{in})$$

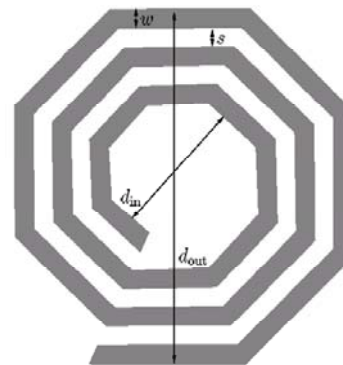
□ 边数, N



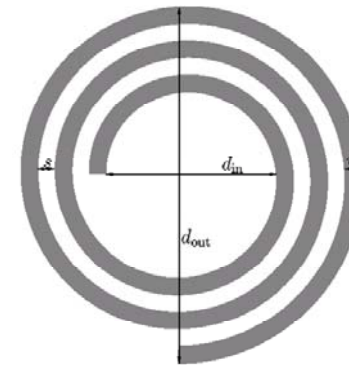
(a) 方形



(b) 六边形



(c) 八边形



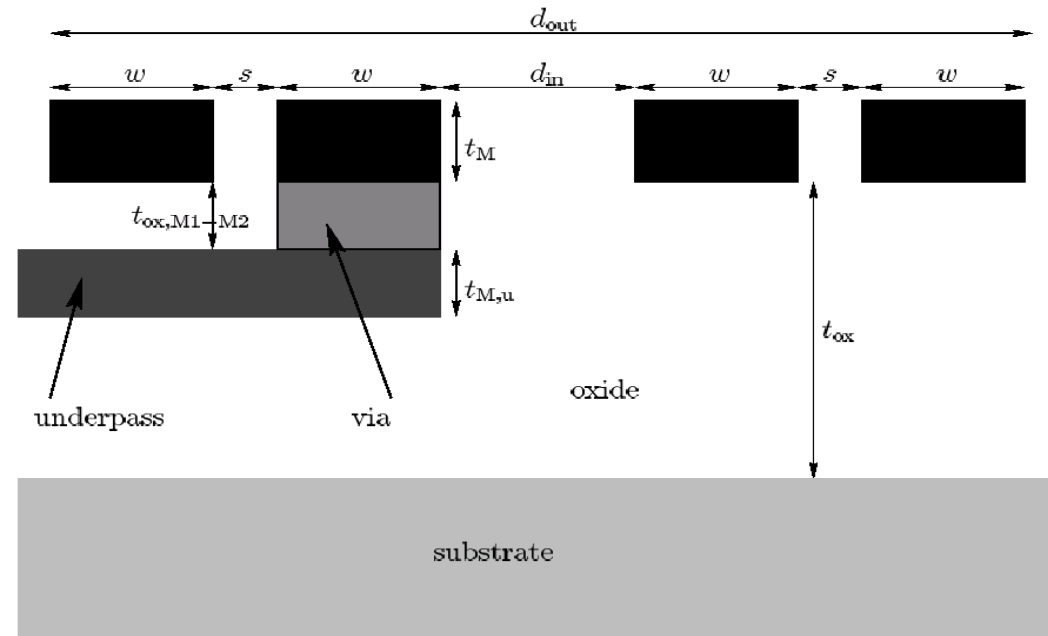
(d) 圆形

平面螺旋电感

平面螺旋电感(II)

● 垂直参数

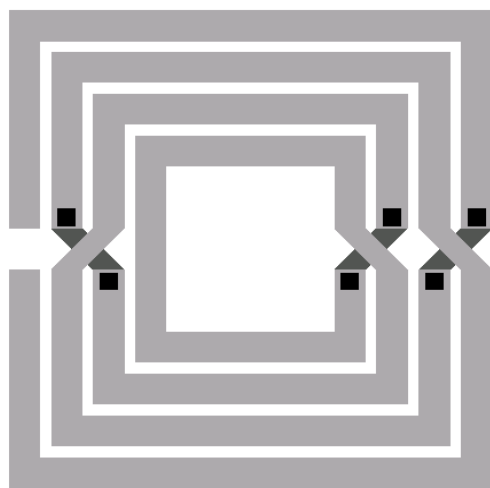
- 金属厚度, t_M , $t_{M,u}$
- 氧化层厚度, t_{ox}
- 金属间氧化层厚度, $t_{ox,M1-M2}$
- 衬底厚度, t_{sub}



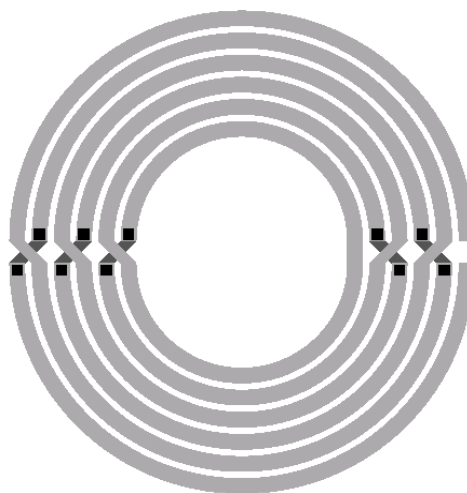
方形电感的垂直参数

其他平面螺旋电感

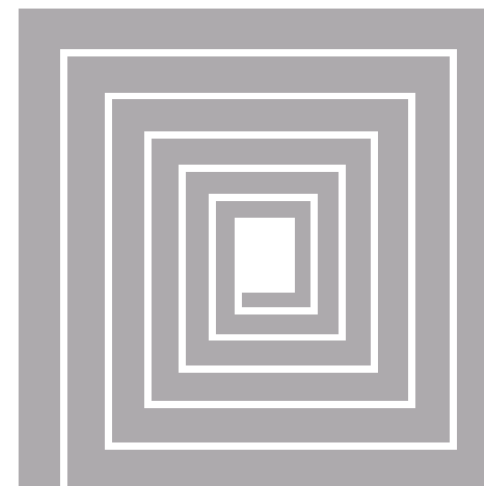
- 对称螺旋电感
- 非等宽螺旋电感



(a) 对称方形电感



(b) 对称圆形电感



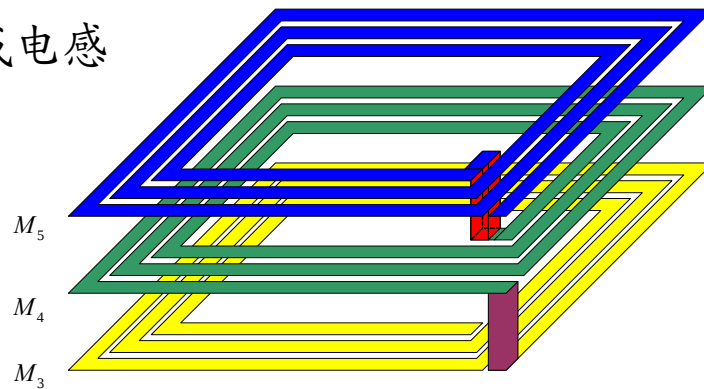
(c) 非等宽方形电感

其他平面螺旋电感

多层叠成螺旋电感

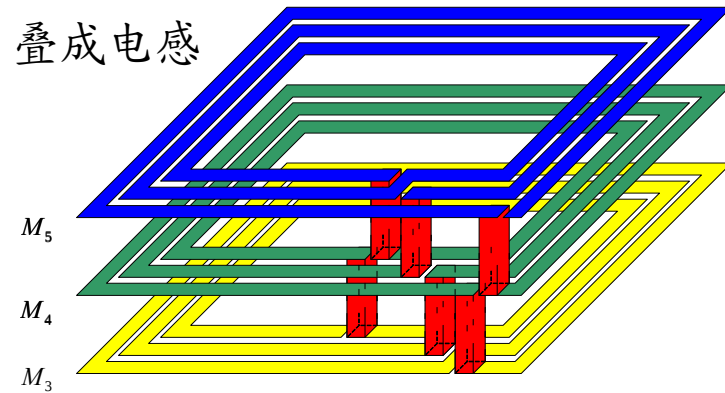
- 叠成电感
- 3D叠成电感

叠成电感



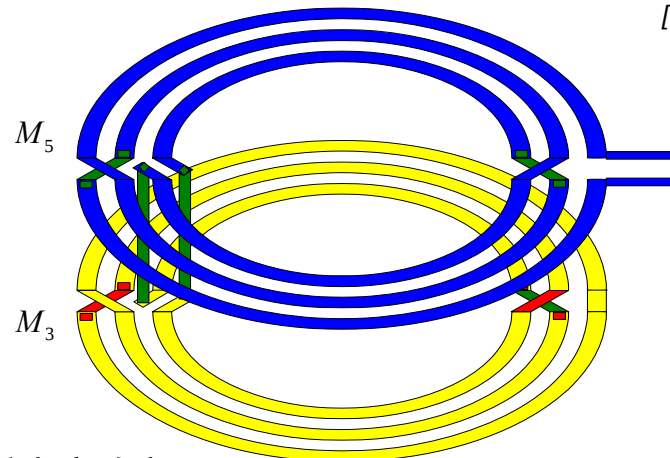
[A. Zolfaghari, B. Razavi, JSSC, April, 2001]

3D 叠成电感



[C.C Tang, S.I. Liu, JSSC, April, 2002]

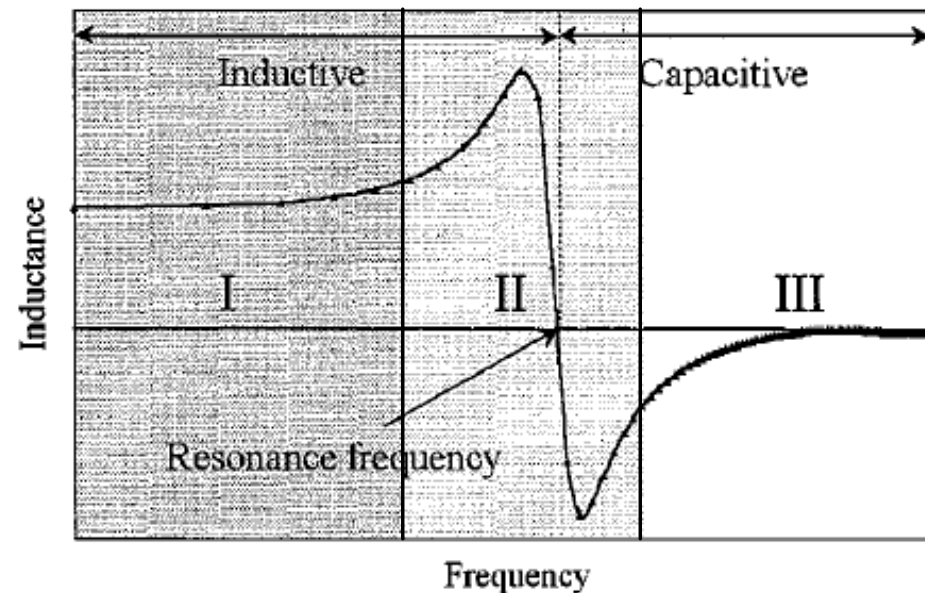
差分叠成电感



片上螺旋电感的分析与建模

● 电感的仿真与建模

- 电磁场仿真工具
- 分段电路模型
- 精简集总电路模型



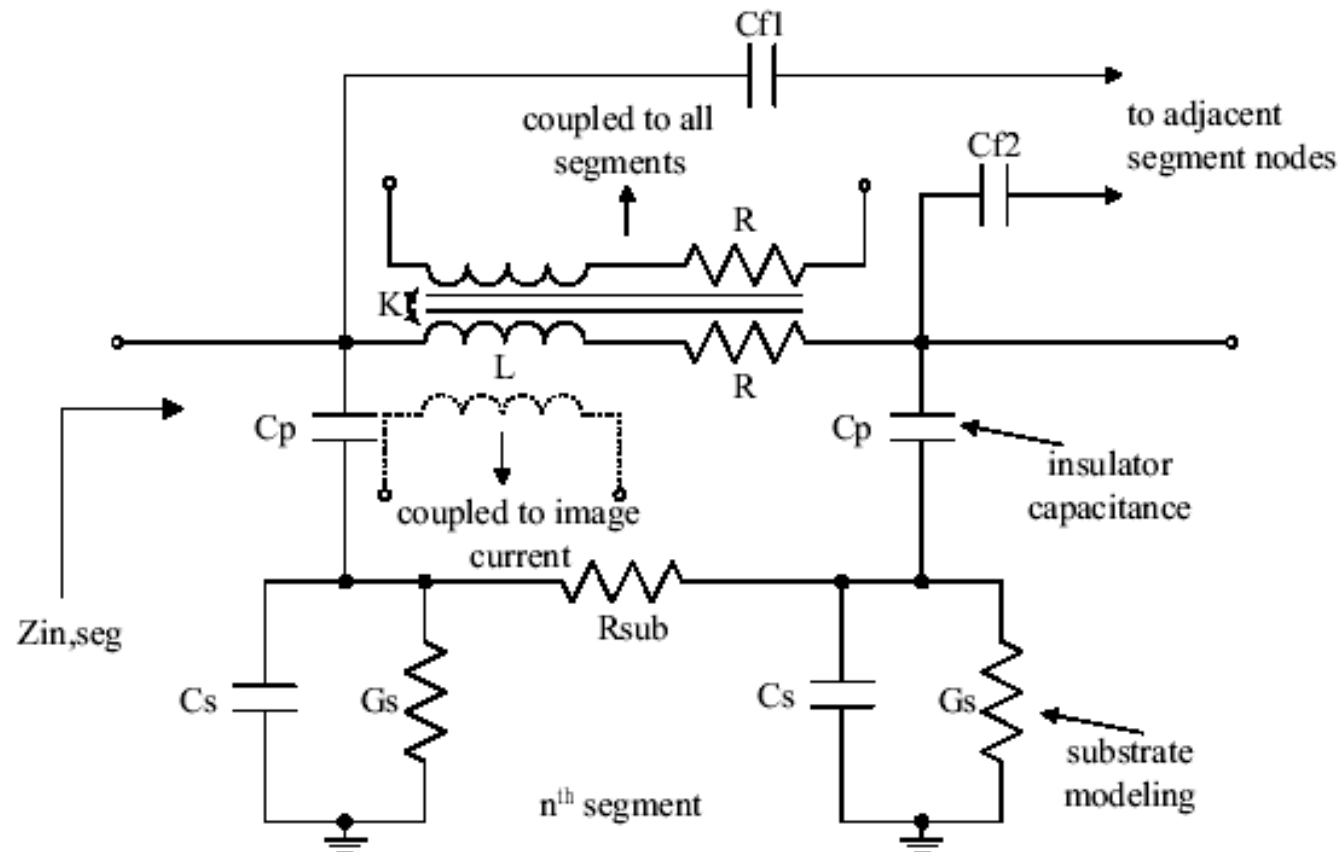
片上电感的典型频响特性

(1)电磁场仿真工具

- Maxwell方程求解器
 - Ansoft, EM-Sonnet, Momentum, Microwave Office
- 优点
 - 高精度, 可用于任何结构分布系统的仿真
- 缺点
 - 速度非常慢
 - 需要大量内存进行计算
 - 软件非常昂贵
 - 对于**SPICE**仿真来说, 模型非常复杂

(2)分段电路模型(I)

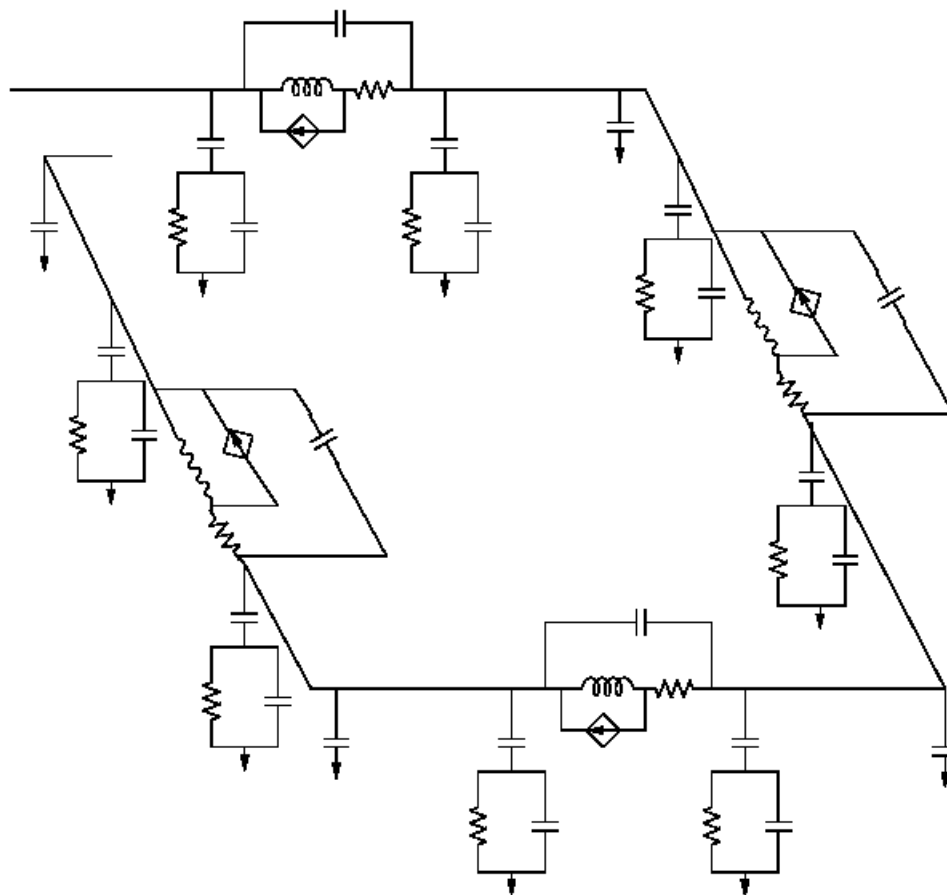
- 对于片上电感的每一条金属建立分段 π 模型



片上电感的每一段金属的两端等效模型

分段电路模型(II)

- 单圈分段模型



单圈分段等效模型

分段电路模型(III)

- 耦合微带线模型

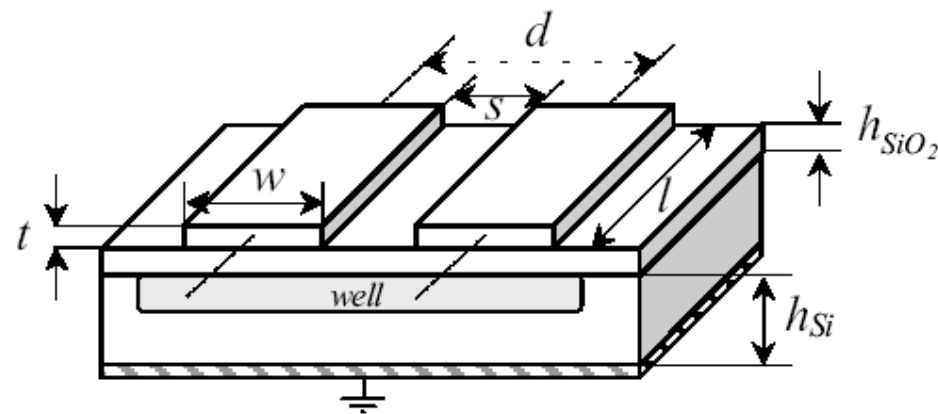


图1 平行微带线的耦合

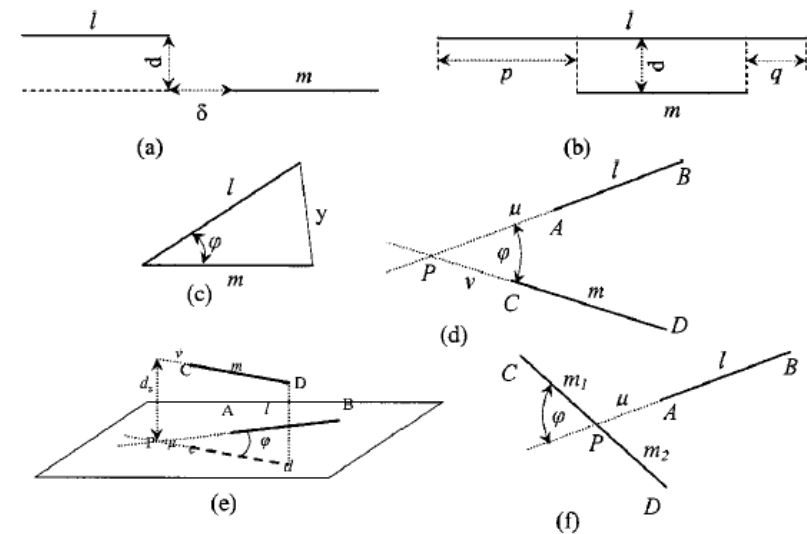


图2 两根金属间的几种耦合方式

分段电路模型(IV)

● π 模型方程

	Equation
$L = 2l \{ \ln[2l / (w+t)] + 0.50049 + (w+t) / 3l \}$	(1)
$R = R_{sh} l / w$	(2)
$C_p = \epsilon_0 \epsilon_r w / h$	(3)
$M = 2lU$	(4)
$K_m = M_{1,2} / \sqrt{L_1 L_2}$	(5)
$2M = (M_{l+m\pm\delta} + M_\delta) - (M_{l\pm\delta} + M_{m\pm\delta})$	(6)
$2M = (M_{m+p} + M_{m+q}) - (M_p + M_q)$	(7)
$M_{lm} = 2 \cos \phi \left[l \tanh^{-1} \left(\frac{m}{l+y} \right) + m \tanh^{-1} \left(\frac{l}{m+y} \right) \right]$	(8)
$M_{lm} = 2 \cos \phi \left[(M_{\mu+l, \nu+m} + M_{\mu\nu}) - (M_{\mu+l, \nu} + M_{\nu+m, \mu}) - \Omega d_z / \sin \phi \right]$	(9)
$\Omega = \frac{\pi}{2} + \tan^{-1} \left[\frac{d_z^2 \cos \phi + lm \sin^2 \phi}{d_z R_l \sin \phi} \right] - \tan^{-1} \left(\frac{d_z \cos \phi}{l \sin \phi} \right) - \tan^{-1} \left(\frac{d_z \cos \phi}{m \sin \phi} \right)$	(10)
$R_{sub} = \rho_{Si} l / (wh_{Si})$	(11)
$C_s = \frac{(w + \Delta w')}{h} \epsilon_0 \epsilon_{r, sub}, \Delta w' = \left(1 + \frac{l}{\epsilon_{r, sub}} \right) \frac{\Delta w}{2}, \Delta w = \frac{t}{\pi} \ln \left[4e / \sqrt{\left(\frac{t}{h} \right)^2 + \left(\frac{l/\pi}{w/t + 1.1} \right)^2} \right]$	(12)
$G_s = \hat{\sigma} \frac{w}{\hat{h}}, \hat{\sigma} = \sigma \left(\frac{l}{2} + \frac{l}{2\sqrt{l + 10h/w}} \right), \hat{h} = \frac{w}{2\pi} \log \left(\frac{8h}{w} + \frac{4w}{h} \right)$	(13)

分段电路模型(V)

- 优点

- ☐ 与电磁场仿真工具相比, 非常简单
- ☐ 易于与 **SPICE** 软件进行集成

- 缺点

- ☐ **SPICE** 网表比较复杂、繁琐
- ☐ 模型中器件数目太多, 降低了 **SPICE** 仿真的速度

(3) 精简集总电路模型(I)

- 简单, 模型中的电阻和电容有明确物理意义

□ 串联电阻 R_s

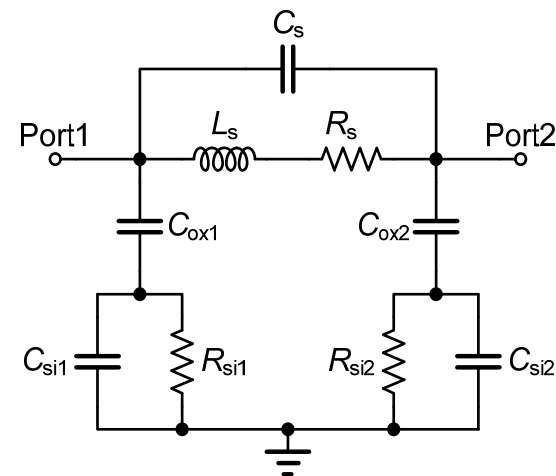
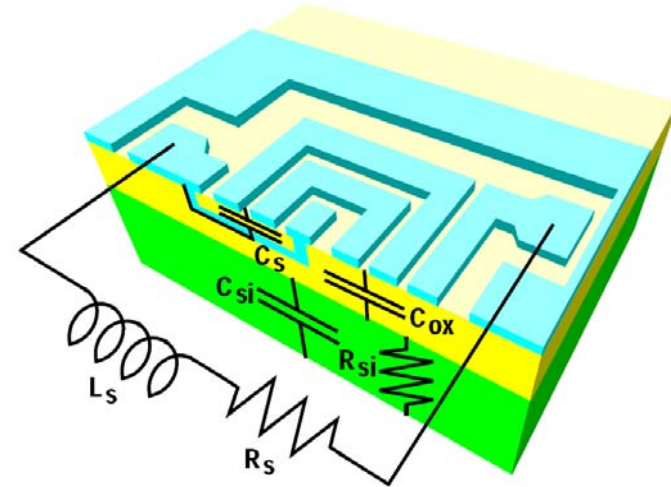
$$R_s \approx \frac{l}{\sigma w \delta (1 - e^{-\frac{t}{\delta}})}$$

σ 是电导率, t 为金属厚度

δ 是趋肤深度 $\delta = \sqrt{\frac{2}{\omega \mu_0 \sigma}}$

□ 金属-衬底间氧化层电容

$$C_{ox1} \approx C_{ox2} \approx \frac{1}{2} \frac{\epsilon_{ox}}{t_{ox}} l w$$



精简集总电路模型(II)

□ 串通电容 C_S

$$C_S \approx \frac{\varepsilon_{ox}}{t_{ox,M1-M2}} n w^2$$

□ 衬底电容

$$C_{si1} \approx C_{si2} \approx \frac{1}{2} C_{sub} l w$$

□ 衬底电阻

$$R_{si1} \approx R_{si2} \approx \frac{2}{G_{sub} l w}$$

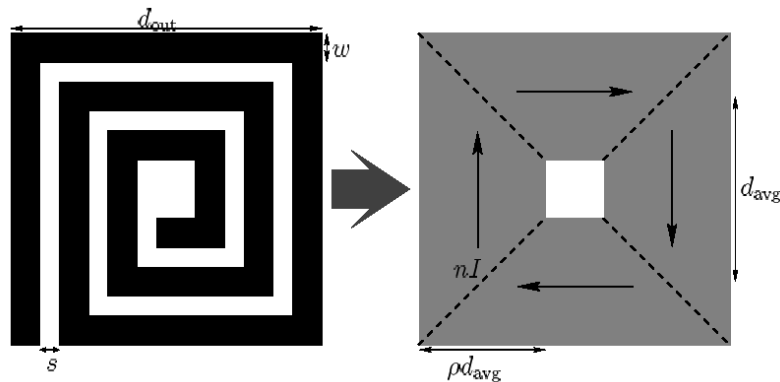
平面螺旋电感的简单精确表达式(I)

● 电流块近似表达式

□ UC Berkeley, Mohan提出的

$$L_{cursh} = \frac{\mu n^2 d_{avg} c_1}{2} [\ln(c_2 / \rho) + c_3 \rho + c_4 \rho^2] \quad \mu \text{ 是磁介质常数, } n \text{ 为圈数}$$

$$d_{avg} = 0.5(d_{out} + d_{in}) \quad \rho = (d_{out} - d_{in}) / (d_{out} + d_{in})$$



电流块近似

Layout	c_1	c_2	c_3	c_4
Square	1.27	2.07	0.18	0.13
Hexagonal	1.09	2.23	0.00	0.17
Octagonal	1.07	2.29	0.00	0.19
Circle	1.00	2.46	0.00	0.20

电流块近似表达式中的系数

平面螺旋电感的简单精确表达式(II)

● 数据拟合多项式

□ 数据拟合技术

$$L_{mon} = \beta d_{out}^{\alpha_1} \omega^{\alpha_2} d_{avg}^{\alpha_3} n^{\alpha_4} s^{\alpha_5}$$

Layout	β	$\alpha_1 (d_{out})$	$\alpha_2 (w)$	$\alpha_3 (d_{avg})$	$\alpha_4 (n)$	$\alpha_5 (s)$
Square	$1.62 \cdot 10^{-3}$	-1.21	-0.147	2.40	1.78	-0.030
Hexagonal	$1.28 \cdot 10^{-3}$	-1.24	-0.174	2.47	1.77	-0.049
Octagonal	$1.33 \cdot 10^{-3}$	-1.21	-0.163	2.43	1.75	-0.049

多项式中的系数

□ 如何拟合

所有变量采用对数形式表示

$$x_1 = \log d_{out} \quad x_2 = \log \omega \quad x_3 = \log d_{avg} \quad x_4 = \log n \quad x_5 = \log s$$

最小均方差拟合

目标函数:

$$\sum_{k=1}^N (y^{(k)} - \alpha_0 - \alpha_1 x_1^{(k)} - \alpha_2 x_2^{(k)} - \alpha_3 x_3^{(k)} - \alpha_4 x_4^{(k)} - \alpha_5 x_5^{(k)})^2$$

平面螺旋电感的简单精确表达式(II)

- 改进型Wheeler公式

- 首先由H.Wheeler提出

- UC Berkeley, Mohan进行了改进

$$L_{mw} = K_1 \mu_0 \frac{n^2 d_{avg}}{1 + K_2 \rho}$$

系数K1和K2是与版图有关的系数, ρ 是填充系数

Layout	K_1	K_2
Square	2.34	2.75
Hexagonal	2.33	3.82
Octagonal	2.25	3.55

改进型Wheeler公式中的系数

优缺点

● 优点

- 精简、集总电路模型，简单、通用且稳定
- 具有物理意义
- 非常容易与**SPICE**软件集成：电路仿真和优化的最佳选择

● 缺点

- 模型与工作频率有关，不适合宽频带应用

等效电容的计算

- 什么是片上电感的等效电容?

- 在自激频率点, 磁场能量峰值与电场能量峰值相等
- 给定电压峰值 V_0 , 电场能量为 $C_{eq}V_0^2/2$

- 第一自激振荡频率 f_{SR}

$$f_{SR} = \left(2\pi\sqrt{L_{eq}C_{eq}}\right)^{-1}$$

- 等效电容模型

- 金属层间电容: C_{M-M}
- 金属与衬底间电容: C_{M-S}

一些假设条件

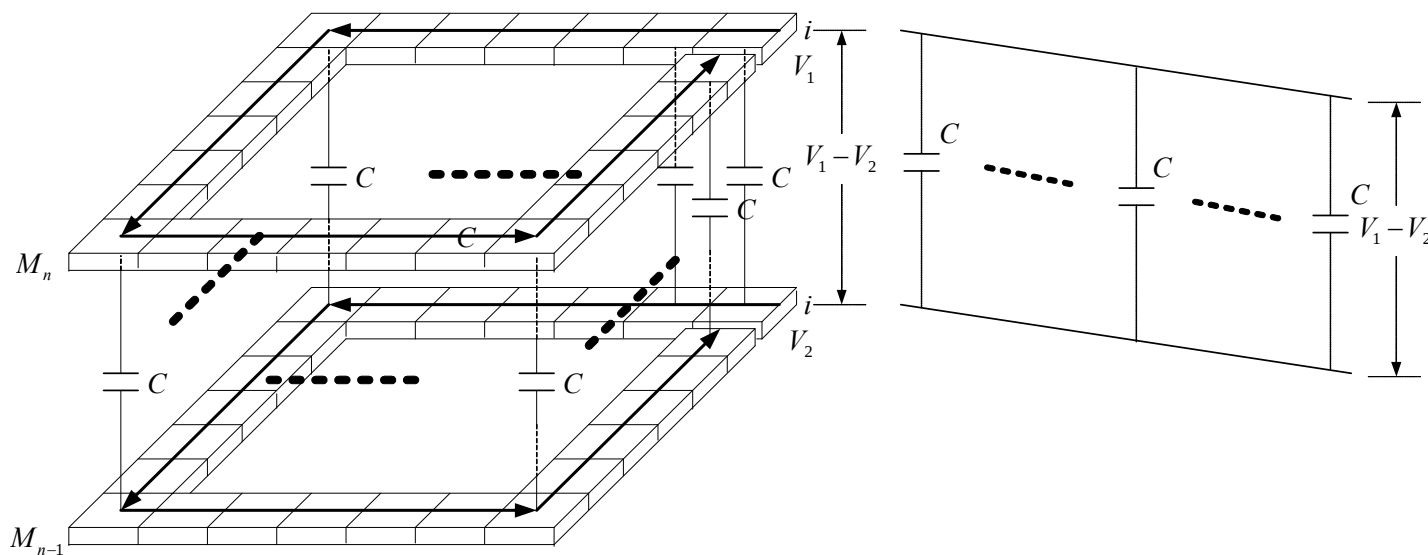
- 每圈线圈的几何参数是相同的
 - 宽度: w
 - 厚度: t
 - 长度: l
- 每圈线圈的电学参数是相同的
 - 金属电导率: ρ
 - 电流: i

金属层间电容: C_{M-M}

● 电场能量

$$E_{e,C_m} = \frac{1}{2} C_m V_{C_m}^2 = \frac{1}{2} \frac{C_{M_n-M_{n-1}} w l}{N} (V_1 - V_2)^2$$

$$E_{e,C} = \sum_{m=1}^N E_{e,C_m} = \sum_{m=1}^N \frac{1}{2} C_m V_{C_m}^2 = \frac{1}{2} C_{M_n-M_{n-1}} w l (V_1 - V_2)^2$$



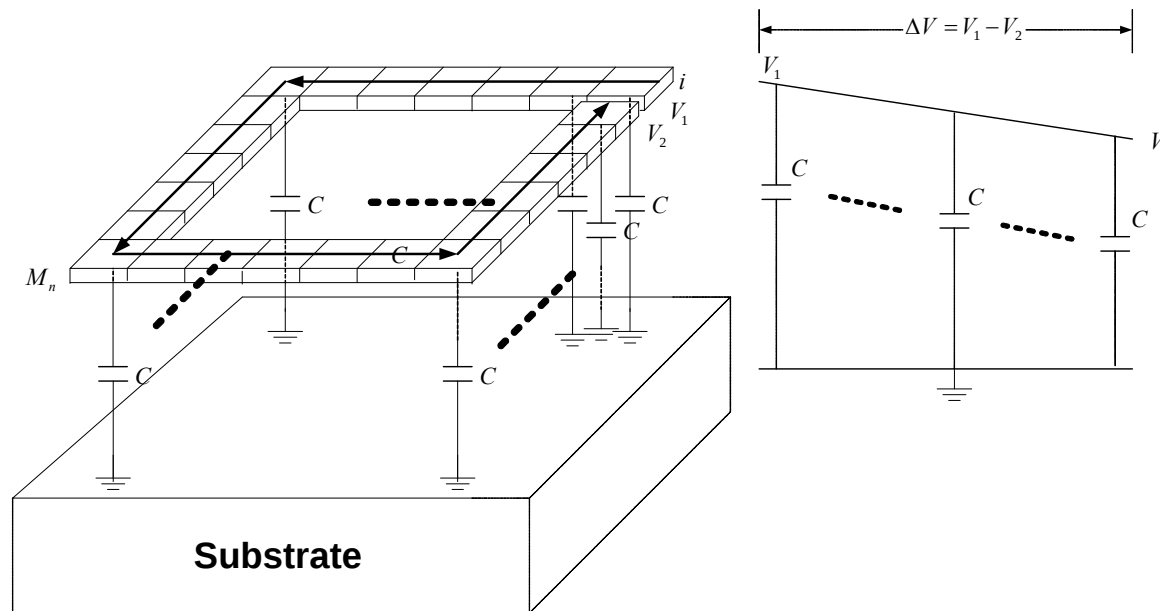
金属层间的分布电容和电压压降图

金属与衬底间电容: C_{M-S}

● 电场能量

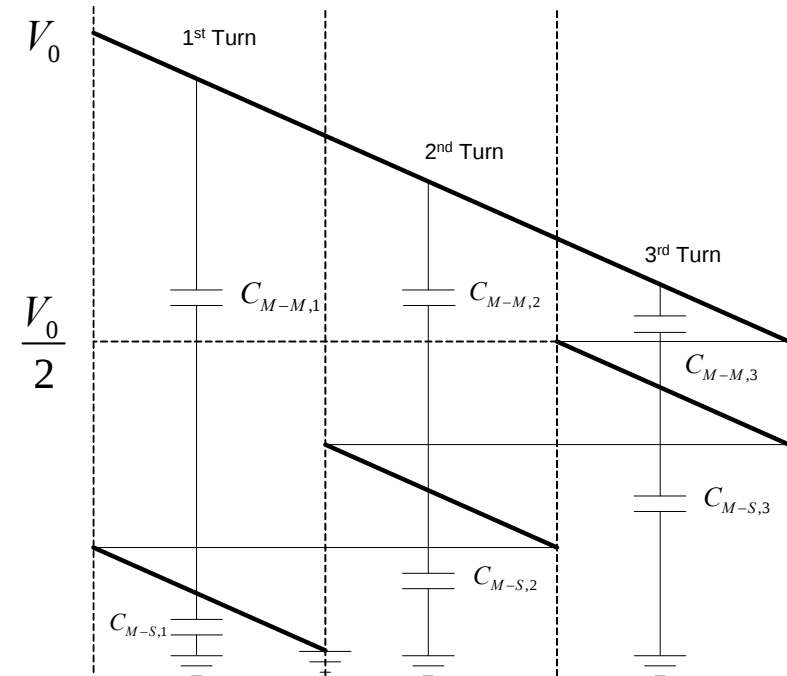
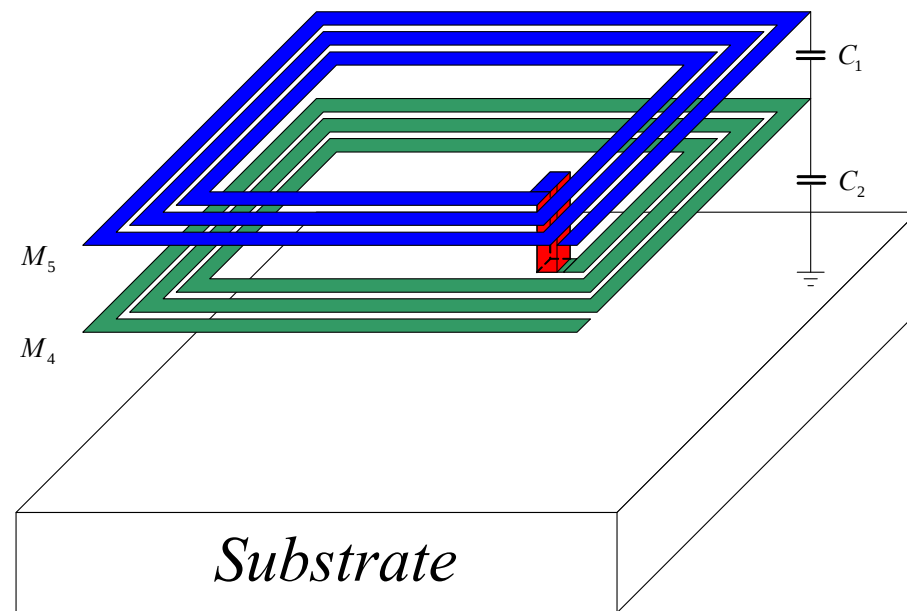
$$E_{e,C_m} = \frac{1}{2} C_m V_{C_m}^2 = \frac{1}{2} \frac{C_{M_n-S} w l}{N} \left(V_1 - \frac{m}{N} \Delta V \right)^2$$

$$E_{e,C} = \sum_{m=1}^N E_{e,C_m} = \sum_{m=1}^N \frac{1}{2} C_m V_{C_m}^2 = \sum_{m=1}^N \frac{1}{2} \frac{C_{M_n-S} w l}{N} \left(V_1 - \frac{m}{N} \Delta V \right)^2 \stackrel{N \rightarrow \infty}{\approx} \frac{1}{6} C_{M_n-S} w l \{ V_1^2 + V_2^2 + V_1 V_2 \}$$



金属与衬底间的分布电容和电压压降图

叠成电感(Stacked)的等效电容



n圈2层叠成电感和电压压降图

电容系数

- K1为金属间电容系数
- K2为金属与衬底间电容系数

$$C_{eq} = \kappa_1 C_1 + \kappa_2 C_2$$

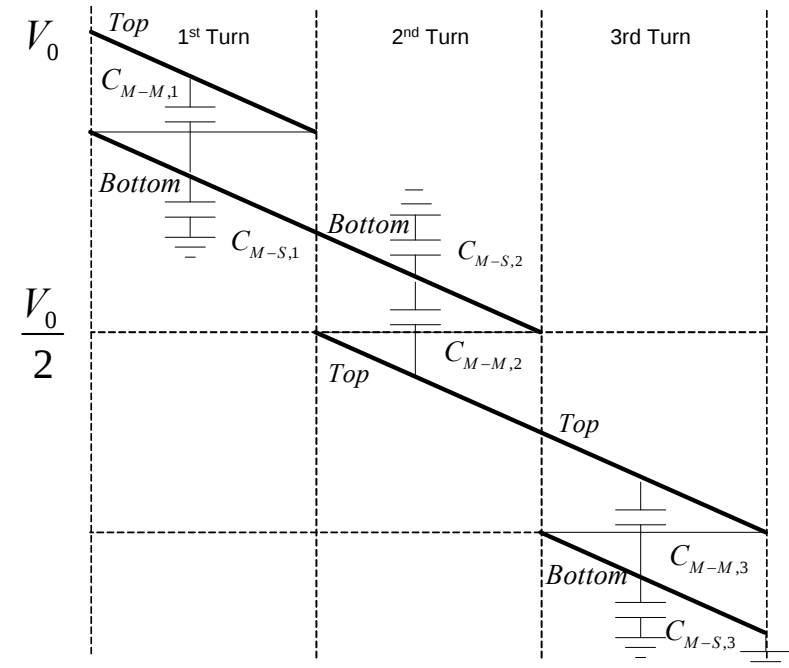
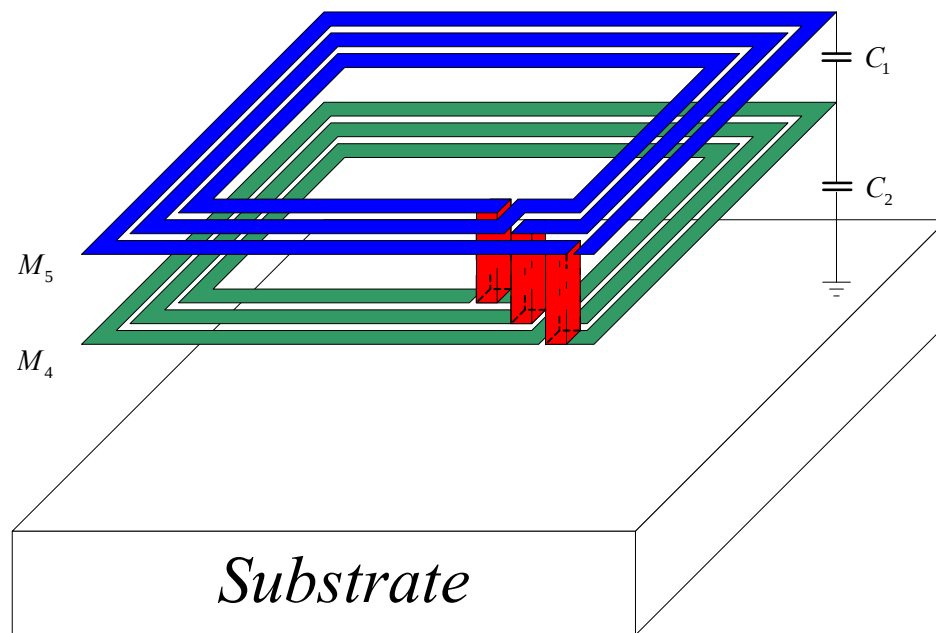
$$C_1 = C_{M_n - M_{n-1}} w \cdot \sum_{k=1}^n l_k \quad C_2 = C_{M_n - S} w \cdot \sum_{k=1}^n l_k \quad l_k = N \cdot \operatorname{tg}\left(\frac{\pi}{N}\right) [d'_{in} + 2(n-k)p]$$

$$\rho_p = p / d'_{in} = (w + s) / d'_{in}$$

$$\kappa_1 = \frac{1}{\left(n \left[1 + (n-1)\rho_p\right]\right)^3} \sum_{m=1}^n \left[1 + 2(n-m)\rho_p\right] \left(\left(n-m + \frac{1}{2}\right) + (n-m)^2 \rho_p \right)^2$$

$$\kappa_2 = \frac{1}{12}$$

3D叠成电感的等效电容



n圈2层3D叠成电感和电压压降图

电容等效系数

$$\kappa_1 = \frac{1}{4} \sum_{m=1}^n \left(\frac{I_m}{2 \sum_{k=1}^n I_k} \right)^3 = \frac{1}{4} \sum_{m=1}^n \left(\frac{d'_{in} + 2(n-m)p}{n[d'_{in} + (n-1)p]} \right)^3$$

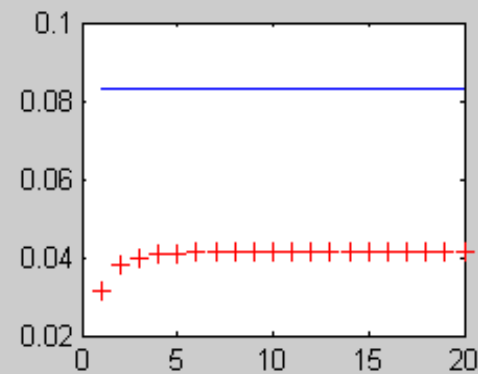
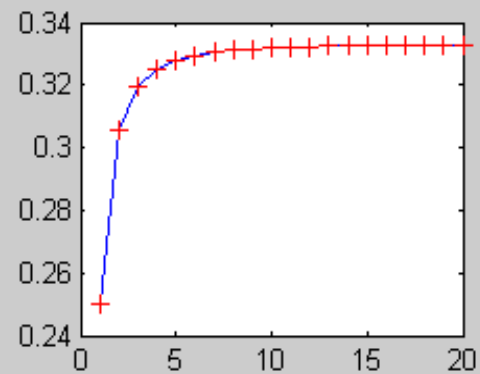
$$\begin{aligned} \kappa_2 = \frac{1}{12(n[1+(n-1)\rho_p])^3} \sum_{m=1}^n (1+2(n-m)\rho_p) & \left\{ \left(2(n-m+1 + \frac{[-1+(-1)^m]}{4}) + (n-m)(2n-2m+1+(-1)^m)\rho_p \right)^2 \right. \\ & + \left(2(n-m + \frac{[1+(-1)^m]}{4}) + (n-m)(2n-2m-1+(-1)^m)\rho_p \right)^2 + \left(2(n-m+1 + \frac{[-1+(-1)^m]}{4}) + \right. \\ & \left. \left. (n-m)(2n-2m+1+(-1)^m)\rho_p \right) \left(2(n-m + \frac{[1+(-1)^m]}{4}) + (n-m)(2n-2m-1+(-1)^m)\rho_p \right) \right\} \end{aligned}$$

比较

K_1

K_2

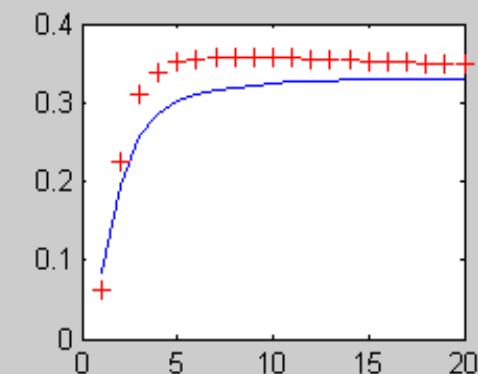
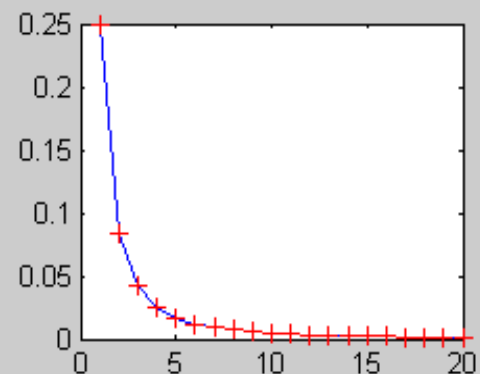
Stacked
叠成电感



叠成电感的特点

- 高自激振荡频率
- 面积小

3D叠成电感



提高品质因数的几种方法

- 电场地屏蔽层
- 多路径分割
- 深阱双反偏pn结隔离

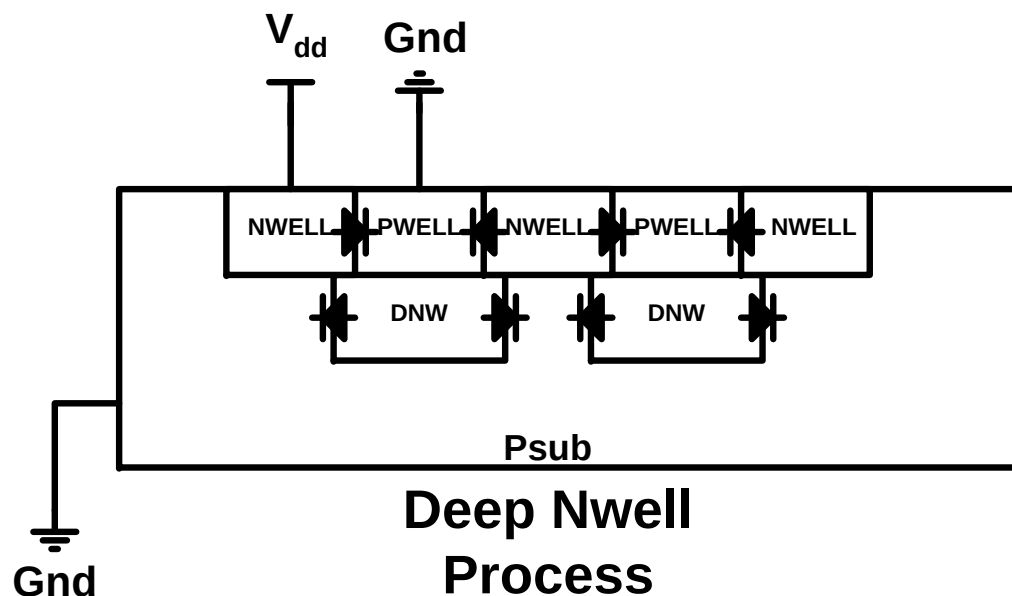


图3 深阱双反偏PN结隔离



图1 电场地屏蔽层

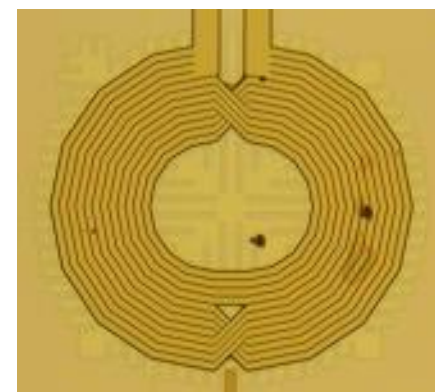
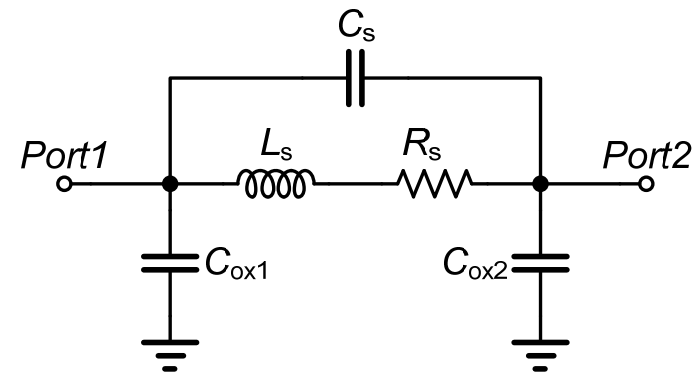
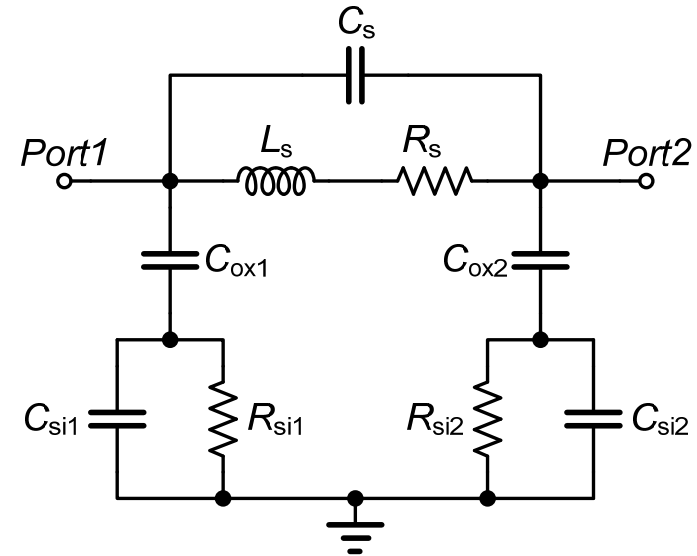


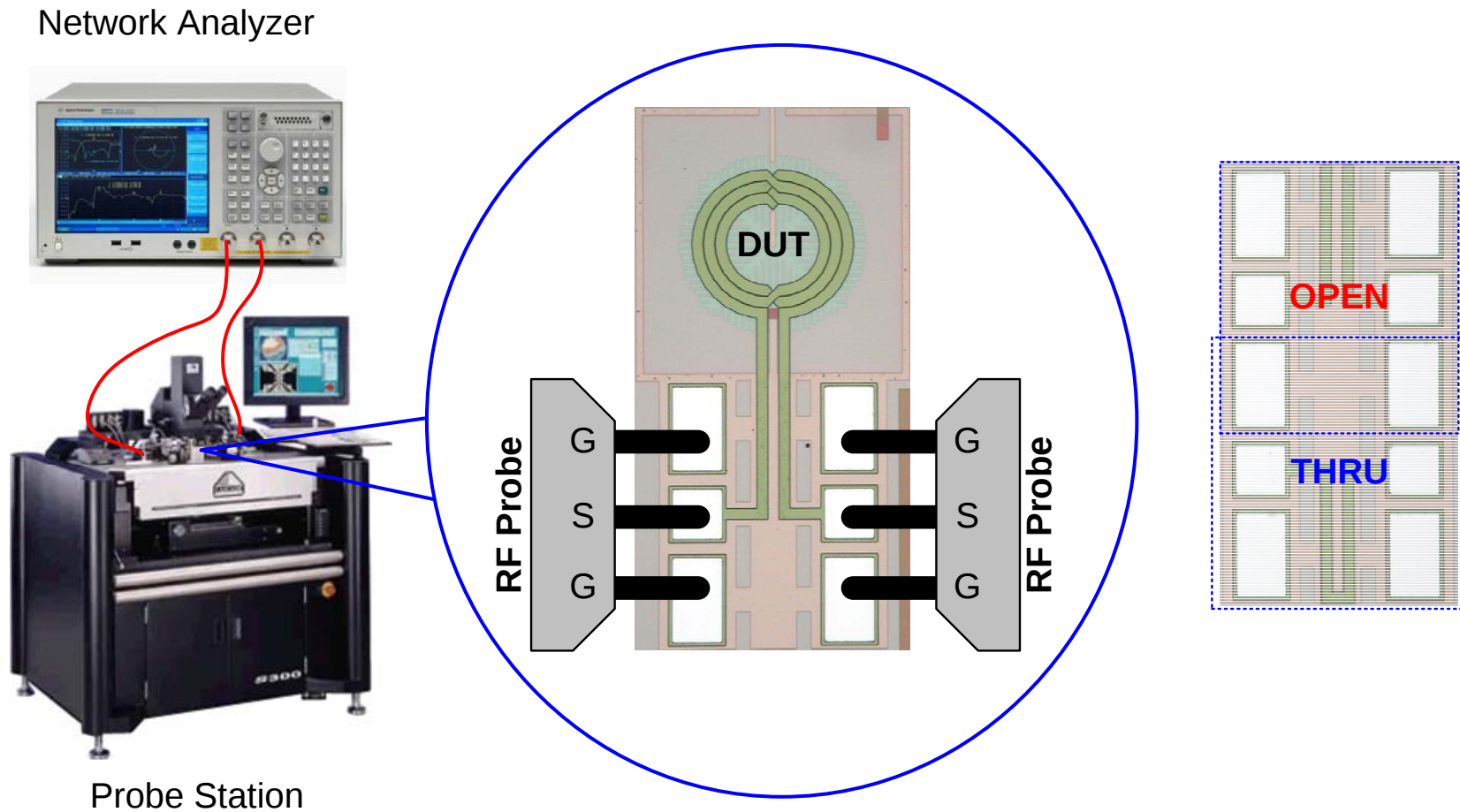
图2 多路径分割

PGS地屏蔽层结构

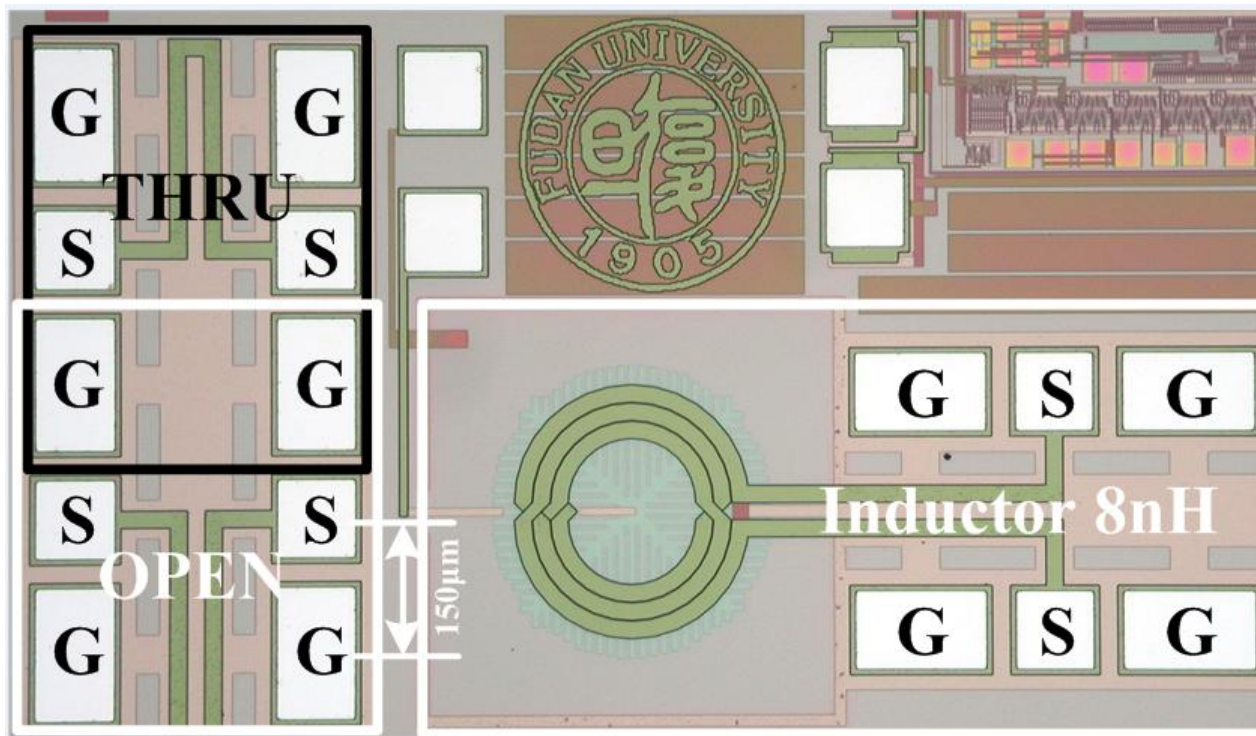


PGS Groud shielded substrate loss

片上电感的在片测试

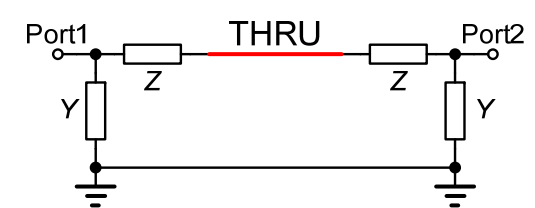
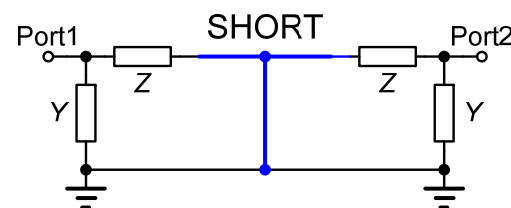
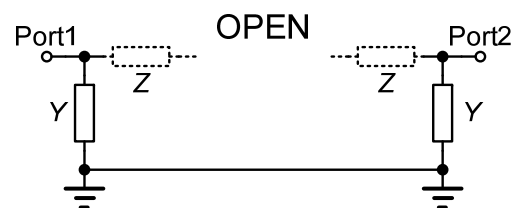
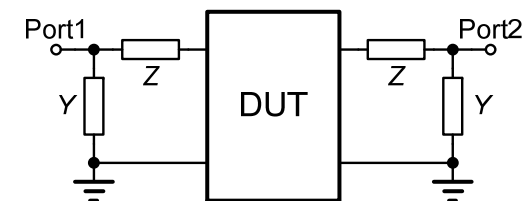


去嵌入结构和方法

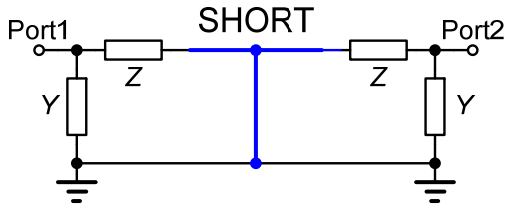
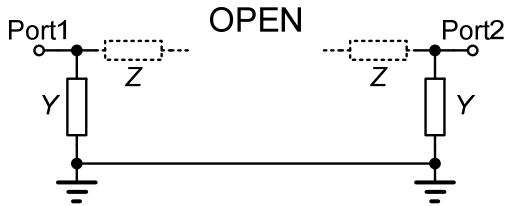
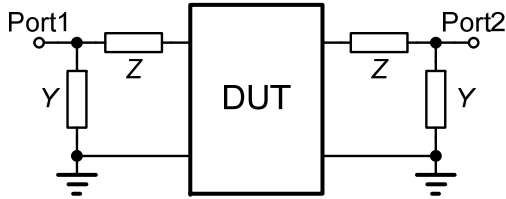


- 去嵌入的作用
去除以下寄生参数

- 探针接触电阻
- PAD寄生电容
- 连接线电阻



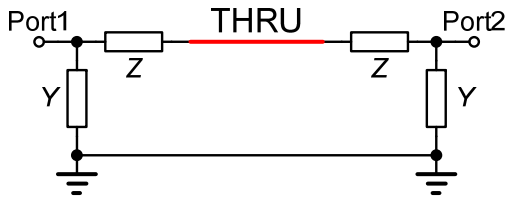
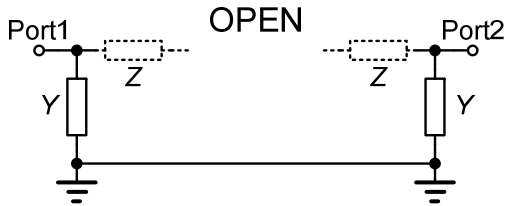
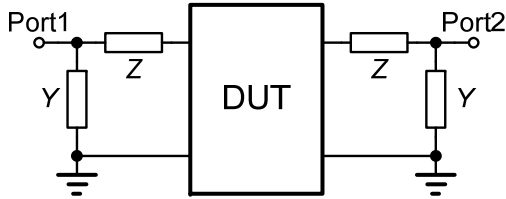
OPEN-SHORT去嵌入



OPEN-SHORT去嵌入步骤

第一步	S参数转换为Y参数 $S_{\text{meas,DUT}} \rightarrow Y_{\text{meas,DUT}}$ $S_{\text{meas,SHORT}} \rightarrow Y_{\text{meas,SHORT}}$ $S_{\text{meas,OPEN}} \rightarrow Y_{\text{meas,OPEN}}$
第二步	DUT和SHORT结构去除PAD并联寄生电容 $Y_{\text{meas,DUT}} - Y_{\text{meas,OPEN}} \rightarrow Y_{\text{DUT-OPEN}}$ $Y_{\text{meas,SHORT}} - Y_{\text{meas,OPEN}} \rightarrow Y_{\text{SHORT-OPEN}}$
第三步	Y参数转换为Z参数 $Y_{\text{DUT-OPEN}} \rightarrow Z_{\text{DUT-OPEN}}$ $Y_{\text{SHORT-OPEN}} \rightarrow Z_{\text{SHORT-OPEN}}$
第四步	去除寄生串联电阻 $Z_{\text{DUT-OPEN}} - Z_{\text{SHORT-OPEN}} \rightarrow Z_{\text{DUT}}$
第五步	Z参数转换为S参数 $Z_{\text{DUT}} \rightarrow S_{\text{DUT}}$

OPEN-THRU去嵌入



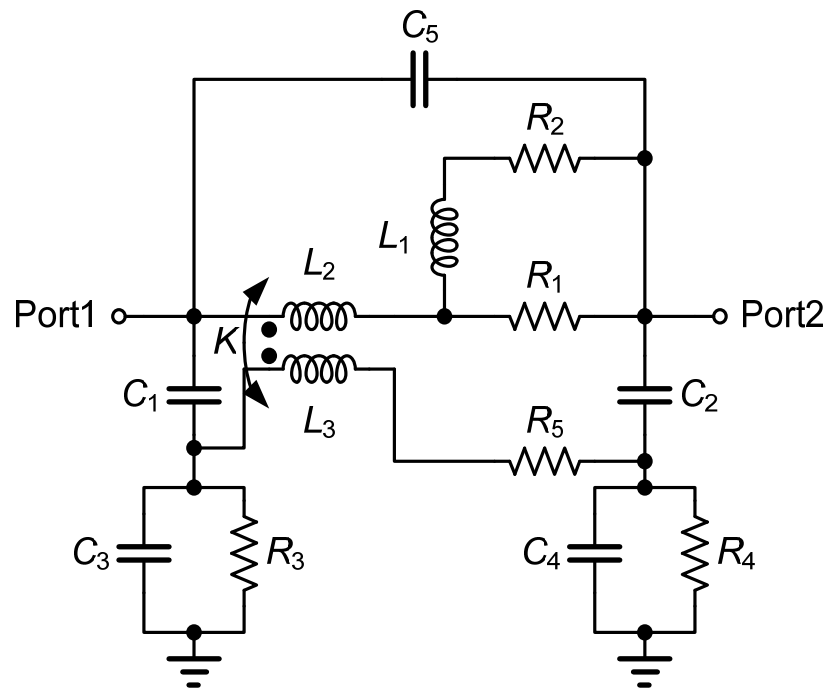
OPEN-THRU去嵌入步骤

第一步	S 参数转换为 Y 参数 $S_{\text{meas,DUT}} \rightarrow Y_{\text{meas,DUT}}$ $S_{\text{meas,THR}} \rightarrow Y_{\text{meas,THRU}}$ $S_{\text{meas,OPEN}} \rightarrow Y_{\text{meas,OPEN}}$
第二步	DUT和SHORT结构去除PAD寄生并联电容 $Y_{\text{meas,DUT}} - Y_{\text{meas,OPEN}} \rightarrow Y_{\text{DUT-OPEN}}$ $Y_{\text{meas,THRU}} - Y_{\text{meas,OPEN}} \rightarrow Y_{\text{THRU-OPEN}}$
第三步	Y 参数转换为 Z 参数 $Y_{\text{DUT-OPEN}} \rightarrow Z_{\text{DUT-OPEN}}$ $Y_{\text{THRU-OPEN}} \rightarrow Z_{\text{THRU-OPEN}}$
第四步	去除寄生串联电阻 $Z_{\text{DUT-OPEN}} - \begin{bmatrix} \frac{1}{2Y_{11,\text{THRU-OPEN}}} & 0 \\ 0 & \frac{1}{2Y_{22,\text{THRU-OPEN}}} \end{bmatrix} \rightarrow Z_{\text{DUT}}$
第五步	Z 参数转换为 S 参数 $Z_{\text{DUT}} \rightarrow S_{\text{DUT}}$

宽频带电感模型

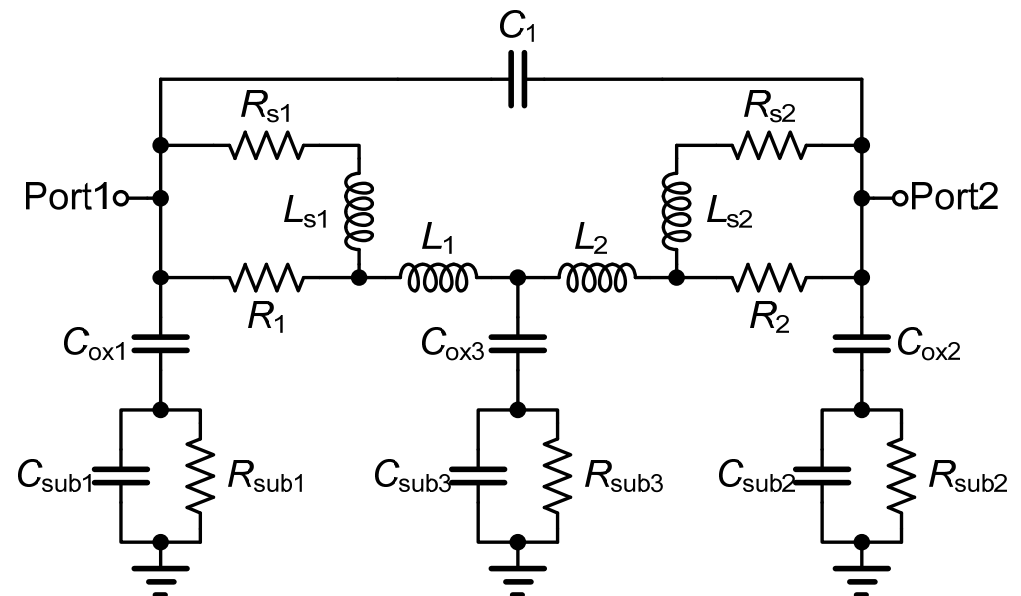
单 π 宽带模型

[J. Kino, VLSI Symp. 2004]



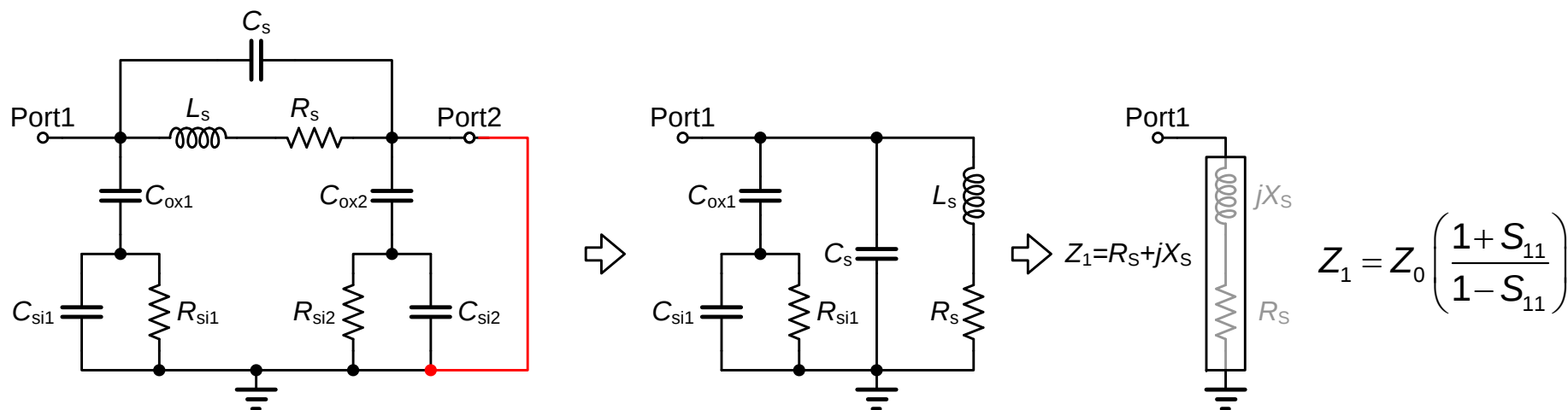
双 π 宽带模型

[Y. Cao, JSSC. March 2003]



RLQ单端等效参数提取(I)

- 单端口阻抗模型：端口**1**或者端口**2**接地



- 等效单端串联电感 L_s
$$L_s = \frac{\text{Im}(Z_1)}{2\pi f}$$
- 等效单端串联电阻 R_s
$$R_s = \text{Re}(Z_1)$$
- 单端串联品质因数 Q_{se}
$$Q_{se} = \frac{\text{Im}(Z_1)}{\text{Re}(Z_1)}$$

单端串联品质因数

$$\frac{1}{j\omega C_{ox1}} + \frac{\frac{1}{j\omega C_{ox1}} R_{si1}}{\frac{1}{j\omega C_{ox1}} + R_{si1}} = \frac{\frac{1}{j\omega C_p} R_p}{\frac{1}{j\omega C_p} + R_p}$$

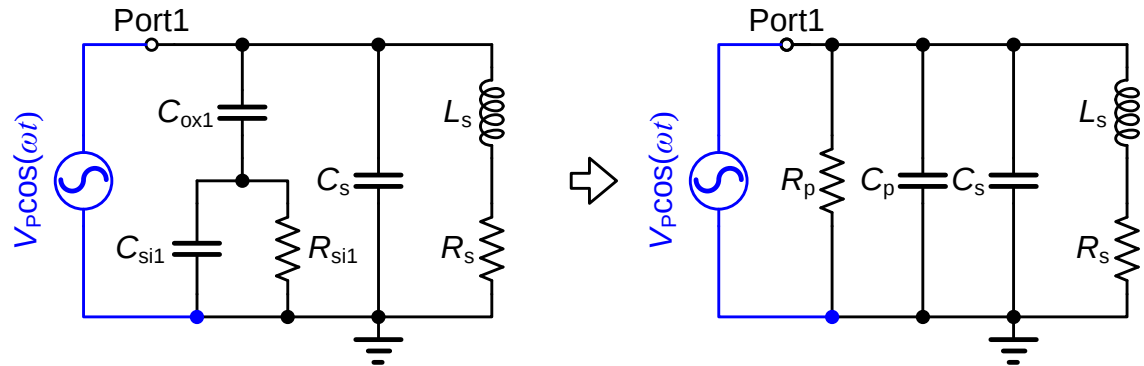
$$R_p = \frac{1}{\omega^2 C_{ox}^2 R_{si1}} + R_{si1} \left(\frac{C_{ox} + C_{si1}}{C_{ox}} \right)^2$$

$$C_p = C_{ox} \frac{1 + \omega^2 (C_{ox} + C_{si1}) C_{si1} R_{si1}^2}{1 + \omega^2 (C_{ox} + C_{si1})^2 R_{si1}^2}$$

$$E_{\text{peak,magnetic}} = \frac{I_{\text{peak}}^2 L_s}{2} = \frac{V_{\text{peak}}^2 L_s}{2 \left[(\omega L_s)^2 + R_s^2 \right]}$$

$$E_{\text{peak,electric}} = \frac{(C_p + C_s) V_{\text{peak}}^2}{2} = \frac{V_p^2 (C_p + C_s)}{2}$$

$$E_{\text{loss in one oscillation cycle}} = \frac{2\pi}{\omega} \cdot \frac{V_p^2}{2} \cdot \left[\frac{1}{R_p} + \frac{R_s}{(\omega L_s)^2 + R_s^2} \right]$$

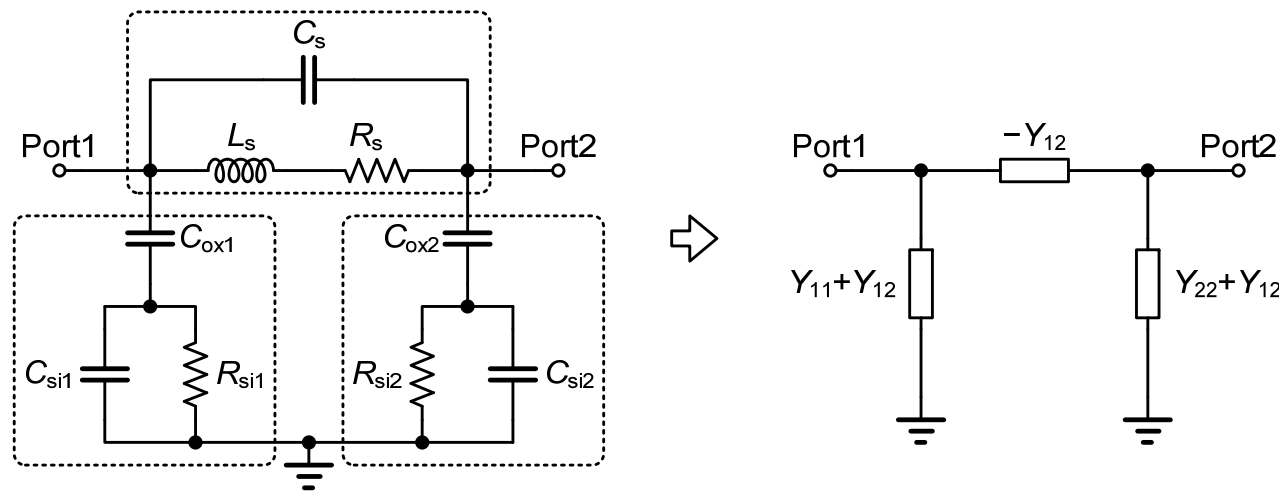


$$Q_{se} = 2\pi \frac{E_{\text{peak,magnetic}} - E_{\text{peak,electric}}}{E_{\text{loss in one oscillation cycle}}}$$

$$\begin{aligned} &= \frac{\overbrace{\frac{Q_{LF}}{\omega L_s}}^{k_{SL}}}{R_s} \times \frac{\overbrace{R_p}^{k_{SL}}}{R_p + \left[(\omega L_s / R_s)^2 + 1 \right] R_s} \\ &\times \underbrace{\left[1 - \frac{R_s^2 (C_s + C_p)}{L_s} - \omega^2 L_s (C_s + C_p) \right]}_{k_{SR}} \end{aligned}$$

RLQ单端等效参数提取(II)

● 双端口单 π Y 模型



- 等效单端串联电感 L_s $L_s = \frac{\text{Im}(1/Y_{11})}{2\pi f}$ or $L_s = \frac{\text{Im}(-1/Y_{12})}{2\pi f}$
- 等效单端串联电阻 R_s $R_s = \text{Re}(1/Y_{11})$ or $R_s = \text{Re}(-1/Y_{12})$
- 单端串联品质因数 Q_{se} $Q_{se} = \frac{\text{Im}(1/Y_{11})}{\text{Re}(1/Y_{11})}$

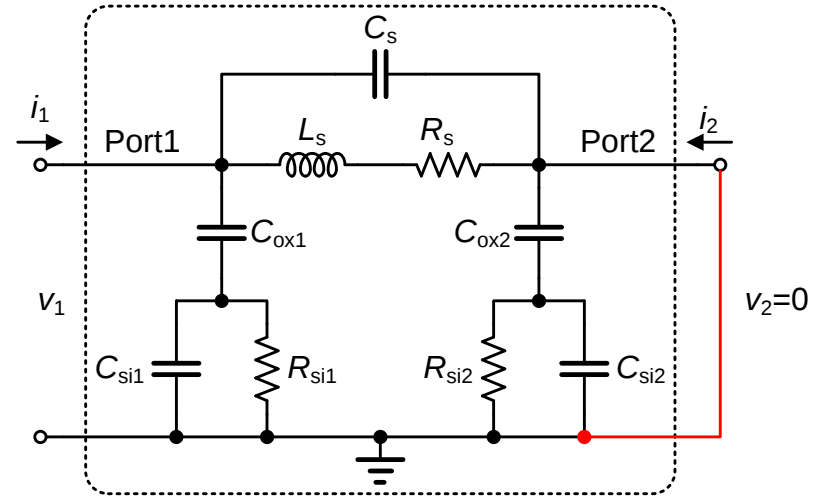
RLQ单端等效参数提取(III)

● 双端口 **Z**模型

$$\begin{bmatrix} V_1 \\ 0 \end{bmatrix} = \begin{bmatrix} Z_{11} & Z_{12} \\ Z_{21} & Z_{22} \end{bmatrix} \begin{bmatrix} i_1 \\ i_2 \end{bmatrix} \quad i_2 = -\frac{Z_{21}}{Z_{22}} i_1$$

$$Z_{\text{port1}} = Z_{11} - \frac{Z_{12}Z_{21}}{Z_{22}}$$

$$Z_{\text{port2}} = Z_{22} - \frac{Z_{12}Z_{21}}{Z_{11}}$$



● 等效单端串联电感 L_s $L_{s,\text{port1,2}} = \text{Im}(Z_{\text{port1,2}})/2\pi f$

● 等效单端串联电阻 R_s $R_{s,\text{port1,2}} = \text{Re}(Z_{\text{port1,2}})$

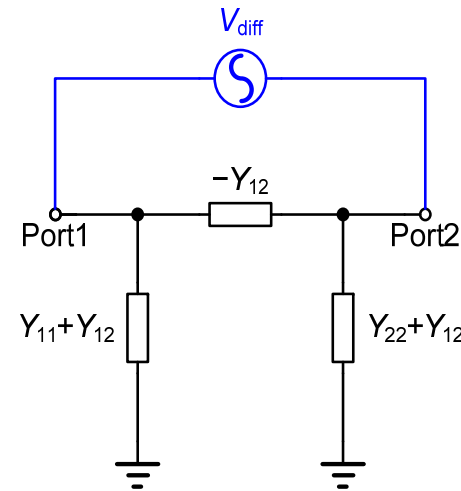
● 单端串联品质因数 Q_{se} $Q_{se,\text{port1,2}} = \frac{\text{Im}(Z_{\text{port1,2}})}{\text{Re}(Z_{\text{port1,2}})}$

RLQ差分等效参数提取(I)

● 差分激励Y参数

$$Z_{\text{diff}} = \left(-\frac{1}{Y_{12}} \right) \parallel \left(\frac{1}{Y_{11} + Y_{12}} + \frac{1}{Y_{22} + Y_{12}} \right)$$

$$= \frac{Y_{11} + Y_{22} + 2Y_{12}}{Y_{11}Y_{22} - Y_{12}^2}$$



● 等效差分串联电感 L_s

$$L_s = \frac{\text{Im}(Z_{\text{diff}})}{2\pi f}$$

● 等效差分串联电阻 R_s

$$R_s = \text{Re}(Z_{\text{diff}})$$

● 差分串联品质因数 Q_{diff}

$$Q_{\text{diff}} = \frac{\text{Im}(Z_{\text{diff}})}{\text{Re}(Z_{\text{diff}})}$$

RLQ差分等效参数提取(II)

- 差分激励 Z 参数

$$\begin{bmatrix} V_1 \\ V_2 \end{bmatrix} = \begin{bmatrix} Z_{11} & Z_{12} \\ Z_{21} & Z_{22} \end{bmatrix} \begin{bmatrix} i_1 \\ -i_1 \end{bmatrix}$$

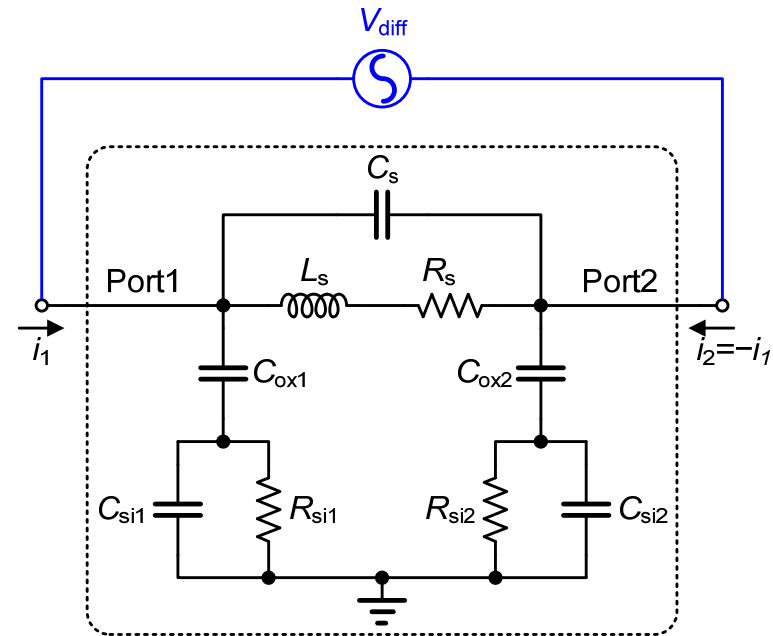
$$Z_{\text{diff}} = \frac{V_1 - V_2}{i_1} = Z_{11} + Z_{22} - Z_{12} - Z_{21}$$

- 等效差分串联电感 L_s

$$L_s = \frac{\text{Im}(Z_{\text{diff}})}{2\pi f}$$

- 等效差分串联电阻 R_s

- 差分串联品质因数 Q_{diff}



$$R_s = \text{Re}(Z_{\text{diff}})$$

$$Q_{\text{diff}} = \frac{\text{Im}(Z_{\text{diff}})}{\text{Re}(Z_{\text{diff}})}$$

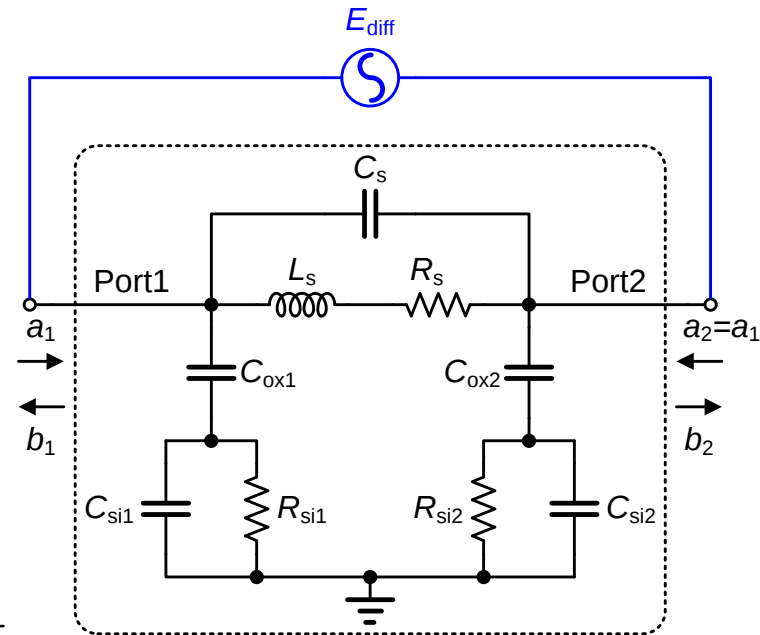
RLQ差分等效参数提取(III)

● 差分激励S参数

$$\begin{bmatrix} b_1 \\ b_2 \end{bmatrix} = \begin{bmatrix} S_{11} & S_{12} \\ S_{21} & S_{22} \end{bmatrix} \begin{bmatrix} a_1 \\ a_2 \end{bmatrix} \quad a_1 = a_2 = a$$

$$S_{\text{diff}} = \frac{b_1 - b_2}{a_1 - a_2} = \frac{(S_{11} + S_{22} - S_{12} - S_{21})a}{2a}$$

$$= \frac{S_{11} + S_{22} - S_{12} - S_{21}}{2} \quad Z_{\text{diff}} = 2Z_0 \frac{1 + S_{\text{diff}}}{1 - S_{\text{diff}}}$$

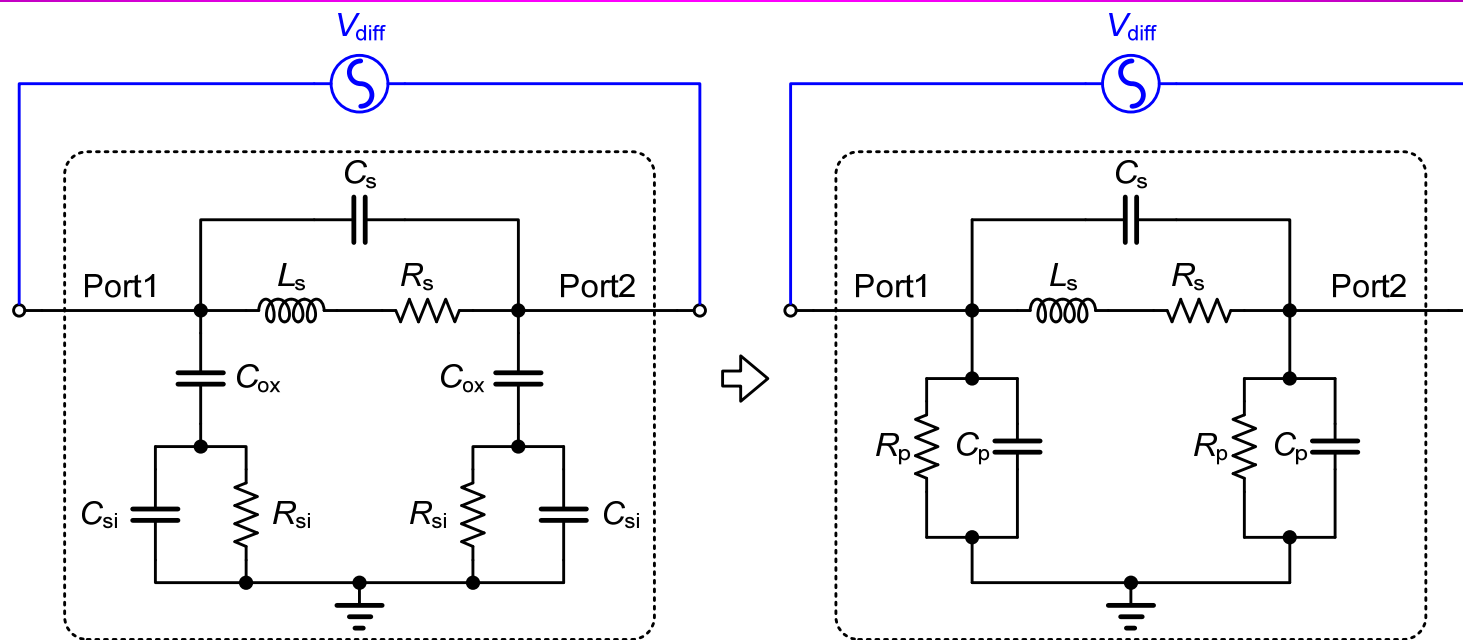


● 等效差分串联电感 L_s $L_s = \text{Im}(Z_{\text{diff}}) / 2\pi f$

● 等效差分串联电阻 R_s $R_s = \text{Re}(Z_{\text{diff}})$

● 差分串联品质因数 Q_{diff} $Q_{\text{diff}} = \frac{\text{Im}(Z_{\text{diff}})}{\text{Re}(Z_{\text{diff}})}$

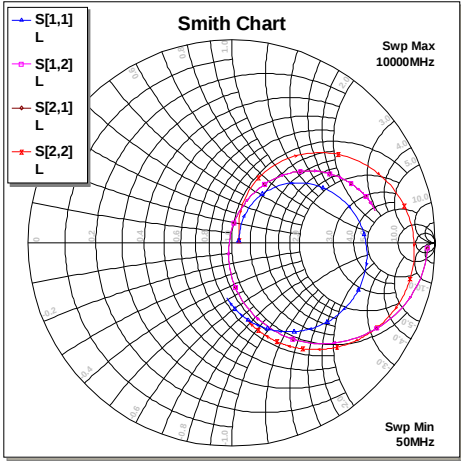
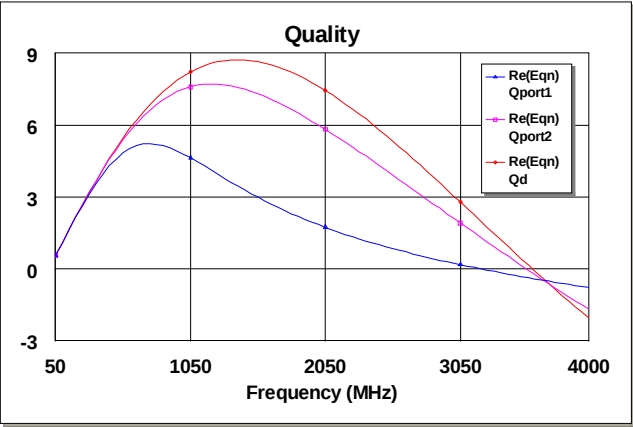
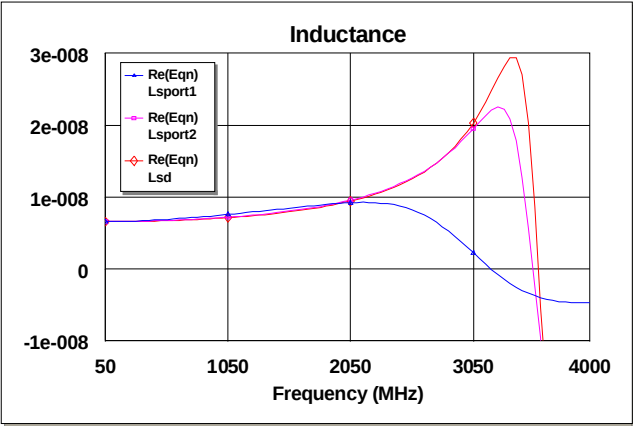
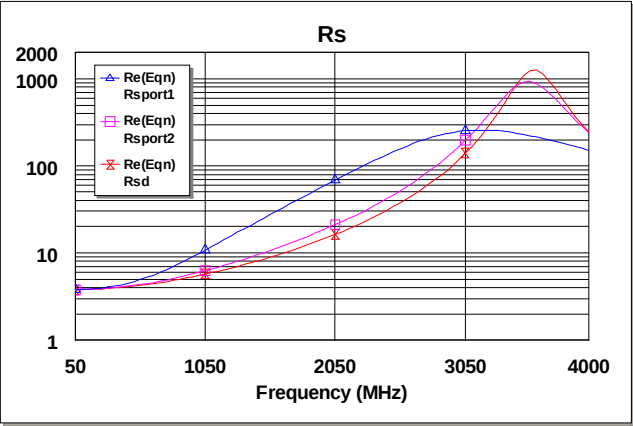
差分串联品质因数



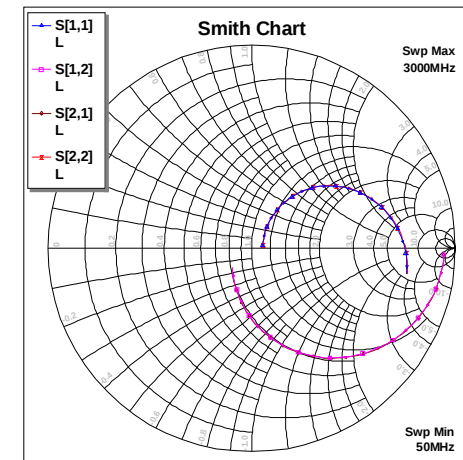
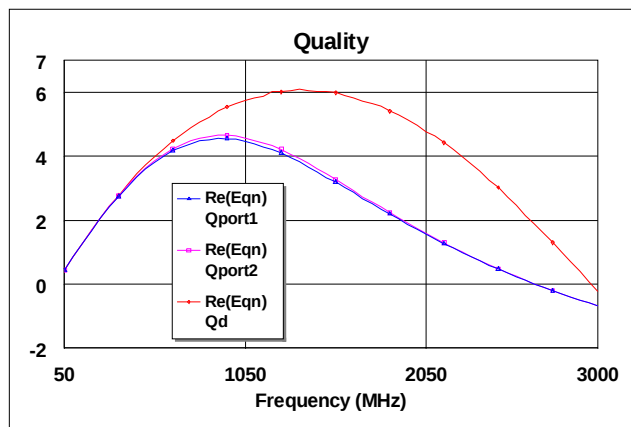
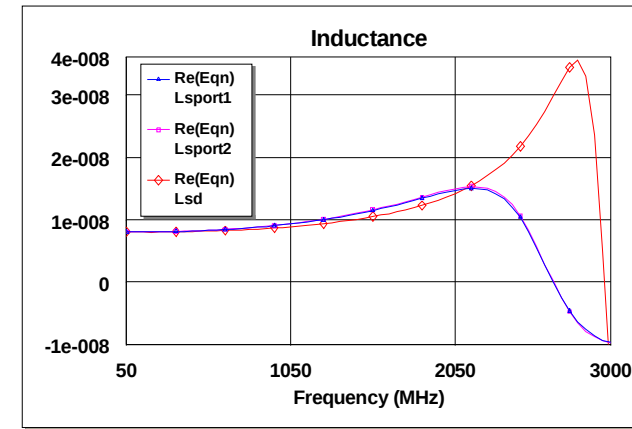
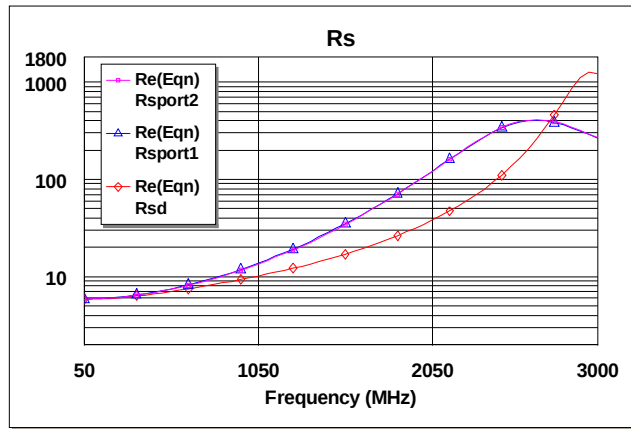
$$Q_{\text{diff}} = 2\pi \frac{E_{\text{peak,magnetic}} - E_{\text{peak,electric}}}{E_{\text{loss in one oscillation cycle}}}$$

$$= \frac{\overbrace{\omega L_s}^{Q_{\text{LF}}}}{R_s} \times \frac{\overbrace{2R_p}^{k_{\text{SL}}}}{\overbrace{2R_p + \left[(\omega L_s / R_s)^2 + 1 \right] R_s}^{k_{\text{SR}}}} \times \left[1 - \frac{R_s^2 \left(C_s + \boxed{C_p/2} \right)}{L_s} - \omega^2 L_s \left(C_s + \boxed{C_p/2} \right) \right]$$

非对称电感 $RLQS$ 曲线



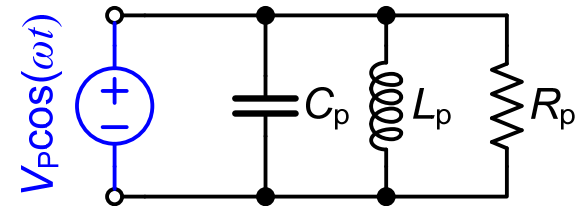
对称差分电感 $RLQS$ 曲线



RLC并联谐振网络品质因数

● 电感Q值

$$Q_L = 2\pi \frac{E_{\text{peak,magnetic}} - E_{\text{peak,electric}}}{E_{\text{loss in one oscillation cycle}}} = 2\pi \frac{\frac{V_p^2}{2\omega^2 L_p} - \frac{C_p V_p^2}{2}}{\frac{2\pi}{\omega} \cdot \frac{V_p^2}{2R_p}}$$



$$= \omega C_p R_p \left[\left(\frac{\omega_0}{\omega} \right)^2 - 1 \right] = \frac{R_p}{\omega L_p} \left[1 - \left(\frac{\omega}{\omega_0} \right)^2 \right]$$

$$E_{\text{peak,magnetic}} = \frac{I_{\text{peak}}^2 L_p}{2} = \frac{V_p^2}{2\omega^2 L_p} = 2E_{\text{average,magnetic}}$$

● 谐振网络Q值@ ω_0

$$Q_L = 2\pi \frac{E_{\text{average,magnetic}} + E_{\text{average,electric}}}{E_{\text{loss in one oscillation cycle}}}$$

$$E_{\text{peak,electric}} = \frac{C_p V_p^2}{2} = 2E_{\text{average,electric}}$$

$$= 2\pi \frac{E_{\text{peak,magnetic}}}{E_{\text{loss in one oscillation cycle}}} = \frac{R_p}{\omega_0 L_p}$$

$$E_{\text{loss in one oscillation cycle}} = \frac{2\pi}{\omega} \cdot \frac{V_p^2}{2R_p}$$

$$= 2\pi \frac{E_{\text{peak,electric}}}{E_{\text{loss in one oscillation cycle}}} = \omega_0 C_p R_p = \frac{R_p}{\sqrt{L_p/C_p}}$$

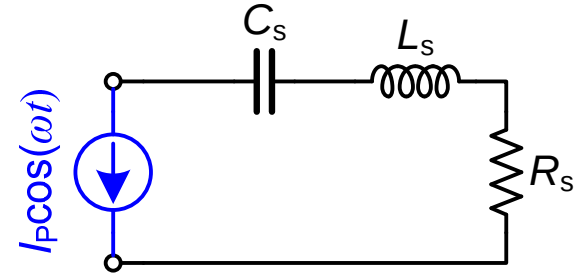
$$\omega_0 = \frac{1}{\sqrt{L_p C_p}}$$

RLC串联谐振网络品质因数

● 电容Q值

$$Q_L = 2\pi \frac{E_{\text{peak,electric}} - E_{\text{peak,magnetic}}}{E_{\text{loss in one oscillation cycle}}} = 2\pi \frac{\frac{I_P^2}{2\omega^2 C_s} - \frac{I_P^2 L_s}{2}}{\frac{2\pi}{\omega} \cdot \frac{I_P^2 R_s}{2}}$$

$$= \frac{\omega L_s}{R_s} \left[\left(\frac{\omega_0}{\omega} \right)^2 - 1 \right] = \frac{1}{\omega C_s R_s} \left[1 - \left(\frac{\omega}{\omega_0} \right)^2 \right]$$



$$E_{\text{peak,magnetic}} = \frac{I_{\text{peak}}^2 L_s}{2} = \frac{I_P^2 L_s}{2} = 2E_{\text{average,magnetic}}$$

$$E_{\text{peak,electric}} = \frac{C_s V_{\text{peak}}^2}{2} = \frac{I_P^2}{2\omega^2 C_s} = 2E_{\text{average,electric}}$$

● 谐振网络Q值@ ω_0

$$Q_L = 2\pi \frac{E_{\text{average,magnetic}} + E_{\text{average,electric}}}{E_{\text{loss in one oscillation cycle}}}$$

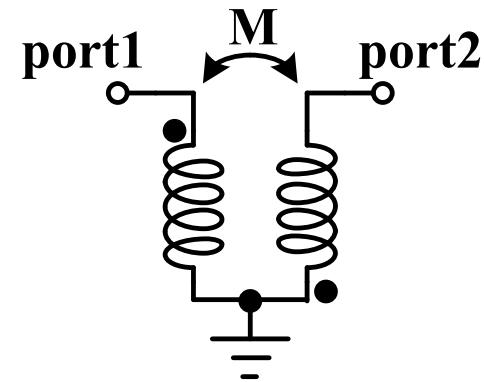
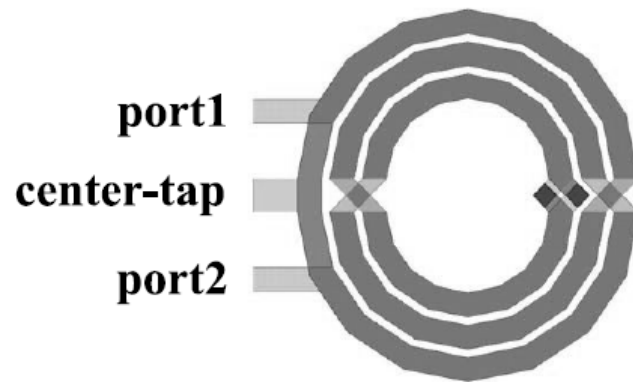
$$= 2\pi \frac{E_{\text{peak,magnetic}}}{E_{\text{loss in one oscillation cycle}}} = \frac{\omega_0 L_s}{R_s}$$

$$= 2\pi \frac{E_{\text{peak,electric}}}{E_{\text{loss in one oscillation cycle}}} = \frac{1}{\omega_0 C_s R_s} = \frac{\sqrt{L_s/C_s}}{R_s}$$

$$E_{\text{loss in one oscillation cycle}} = \frac{2\pi}{\omega} \cdot \frac{I_P^2 R_s}{2}$$

$$\omega_0 = \frac{1}{\sqrt{L_s C_s}}$$

中心抽头差分电感



● 中心抽头差分电感应用场合

- 采用中心抽头差分电感的压控振荡器的谐振网络
- 用于正交压控振荡器中的源极二次谐波耦合
- 全差分低噪声放大器和混频器的负载谐振网络

单端口 S 参数测量

● 单端口 S 参数测量

$$Z_{in} = Z_0 \left(\frac{1 + S_{11}}{1 - S_{11}} \right)$$

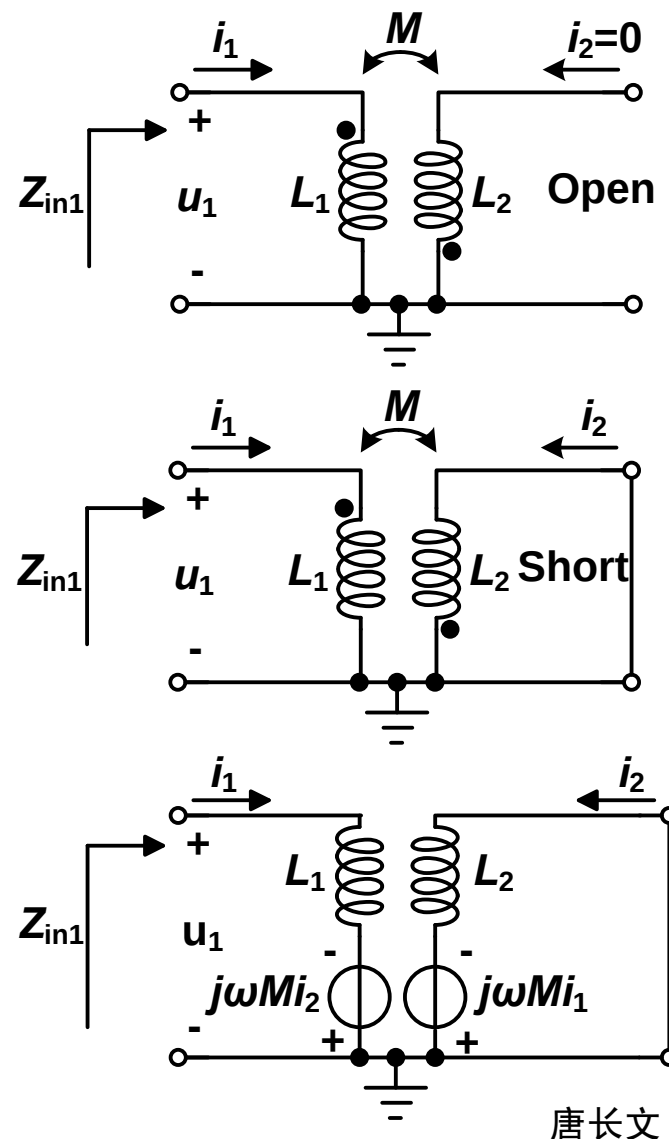
□ 端口 2 开路

$$Z_{in} = j\omega L_1$$

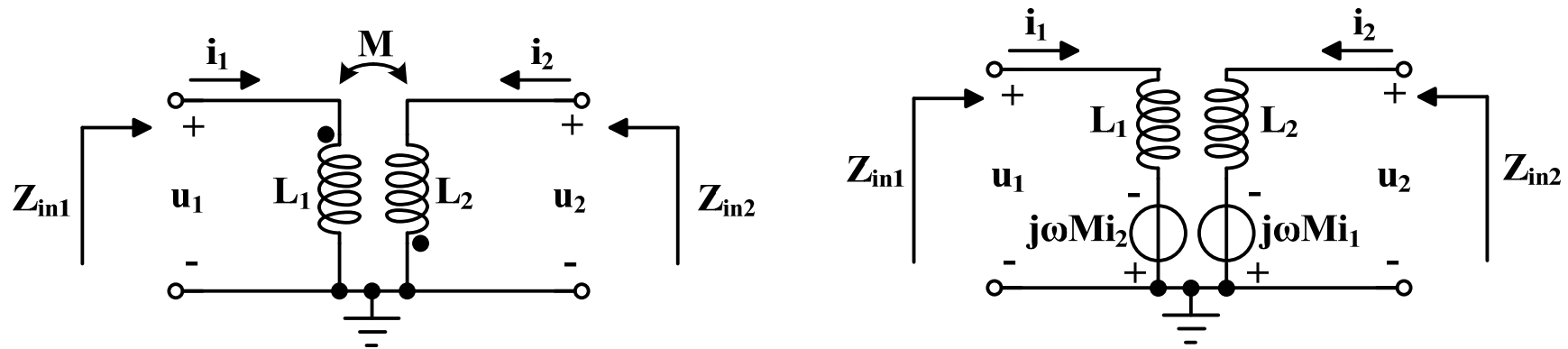
□ 端口 2 短路

$$\begin{aligned} j\omega L_1 i_1 - j\omega M i_2 &= u_1 \\ -j\omega M i_1 + j\omega L_2 i_2 &= 0 \end{aligned} \quad L_1 = L_2 = L$$

$$Z_{in1} = \frac{u_1}{i_1} = j\omega L \left(1 - \frac{M^2}{L^2} \right) = j\omega L (1 - k^2)$$



宽带 180° 相移网络的双端口S参数测量



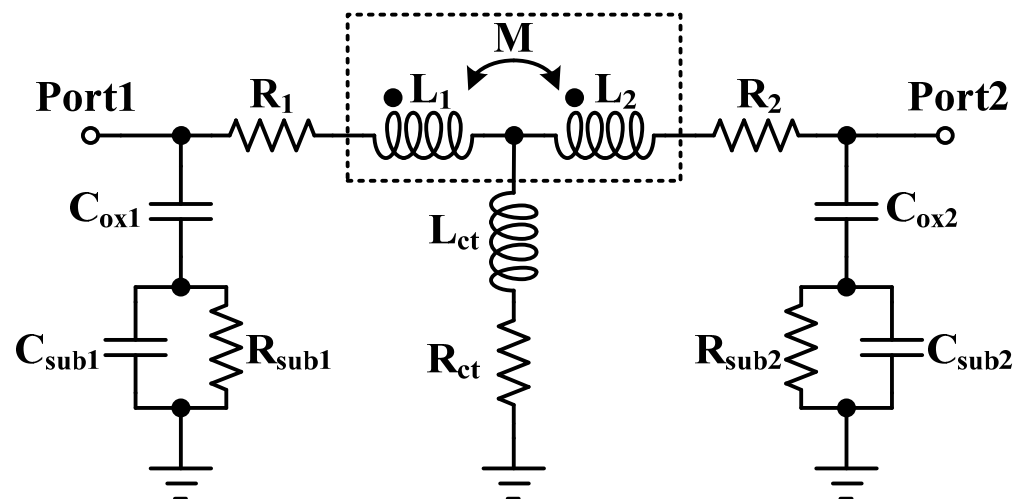
$$\begin{aligned} j\omega L_1 i_1 - j\omega M i_2 &= u_1 & L_1 &= L_2 = L \\ -j\omega M i_1 + j\omega L_2 i_2 &= u_2 & u_2 &= -u_1 \end{aligned}$$

$$Z_{in1} = \frac{u_1}{i_1} = j\omega L (1+k) = j\omega (L+M)$$

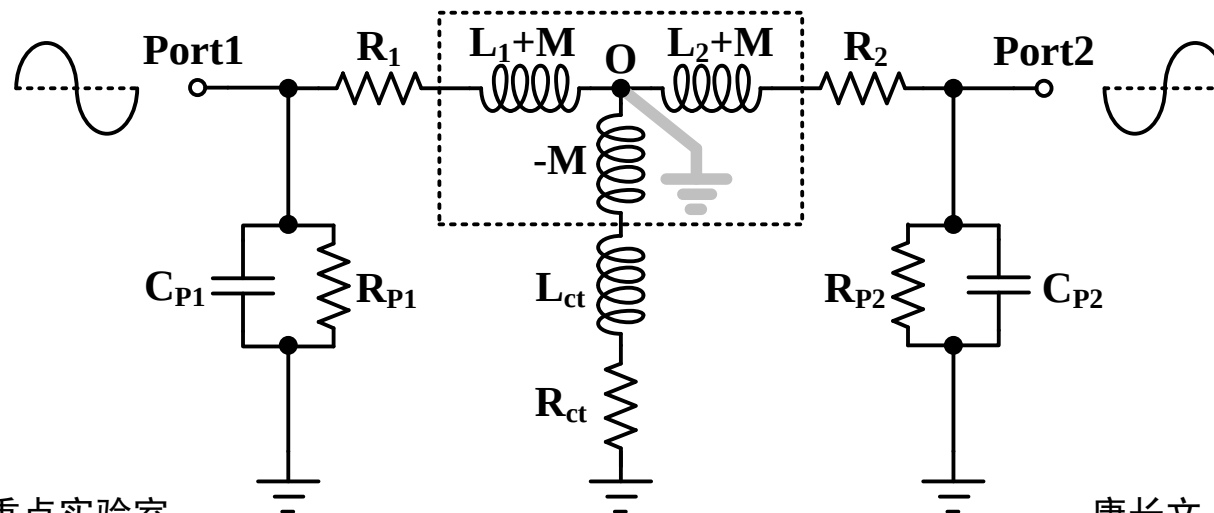
$$Z_{in2} = \frac{u_2}{i_2} = j\omega L (1+k) = j\omega (L+M)$$

中心抽头等效模型

● 集总电路模型

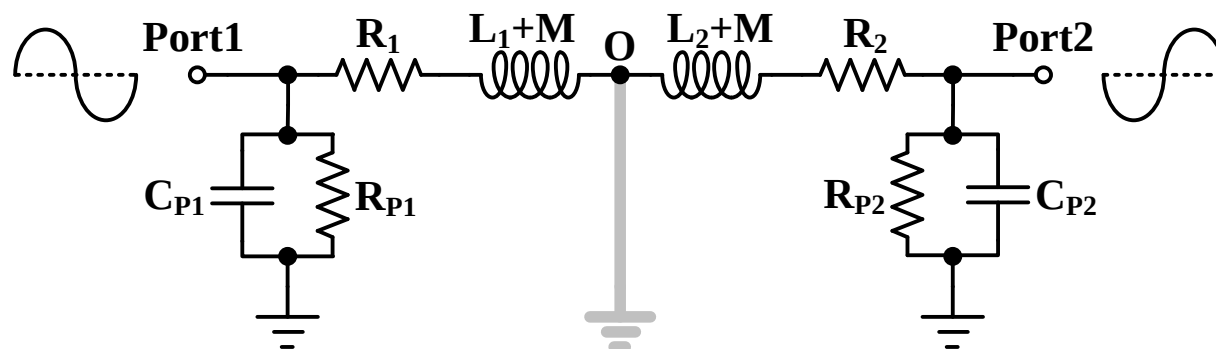


● 去耦等效集总电路模型

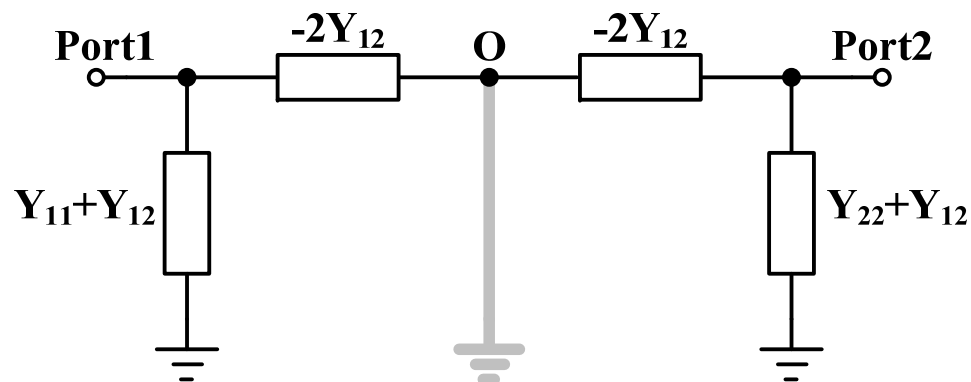


差分激励等效模型

● 差分激励的交流等效模型



● 中心抽头等效模型



差分激励单端阻抗和差分阻抗

● 单端阻抗

$$R_{se} + jX_{se} = \frac{1}{Y_{11} - Y_{12}}$$

● 差分阻抗

$$R_{diff} + jX_{diff} = \left(-\frac{1}{Y_{12}} \right) \parallel \left(\frac{1}{Y_{11} + Y_{12}} + \frac{1}{Y_{22} + Y_{12}} \right) = \frac{Y_{11} + Y_{22} + 2Y_{12}}{Y_{11}Y_{22} - Y_{12}^2}$$

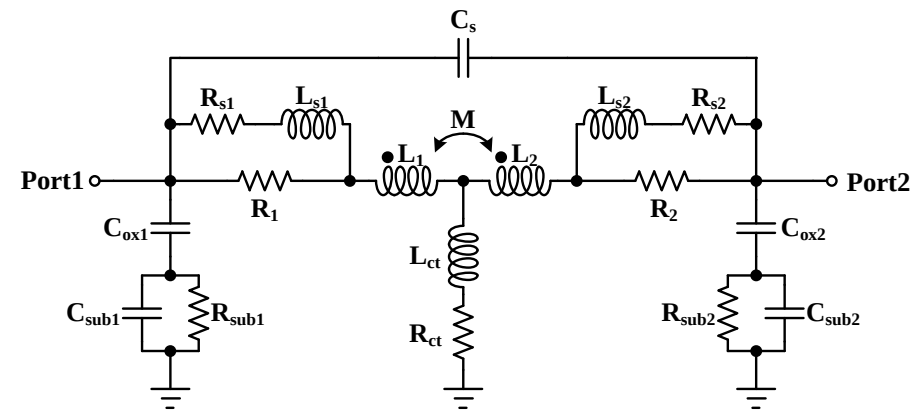
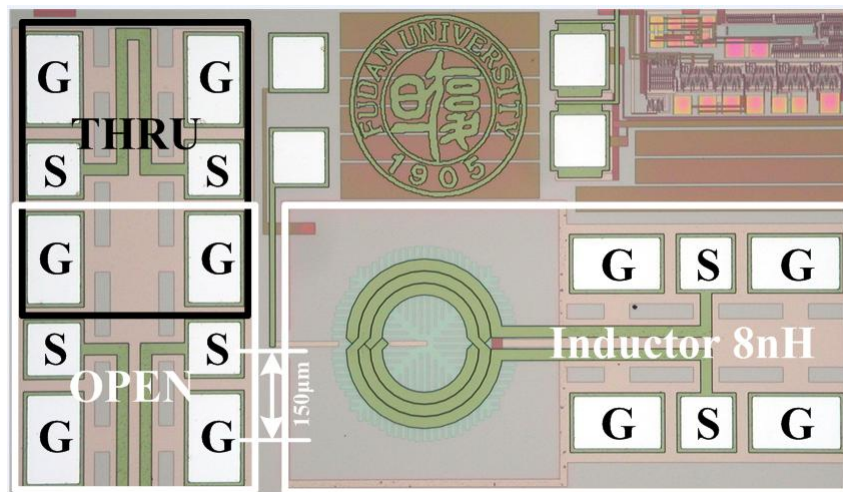
● **RLQ**参数提取

$$R_{eff} = \operatorname{Re}[R + jX] \quad L_{eff} = \frac{\operatorname{Im}[R + jX]}{2\pi f} \quad = \frac{2}{Y_{11} - Y_{12}} \quad (Y_{11} = Y_{22})$$

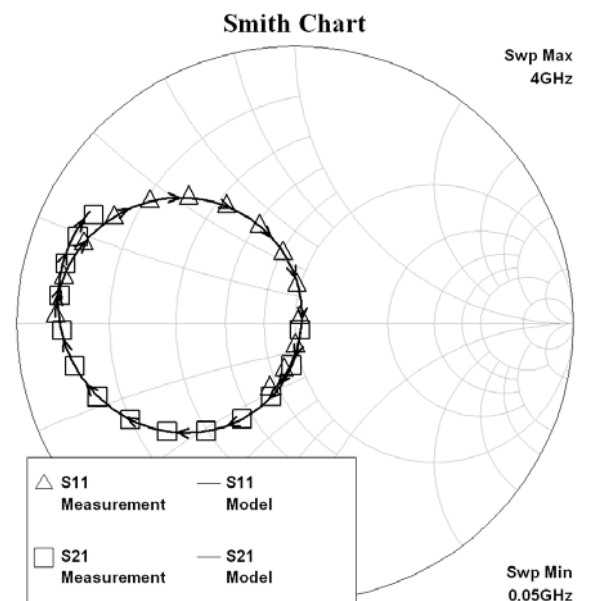
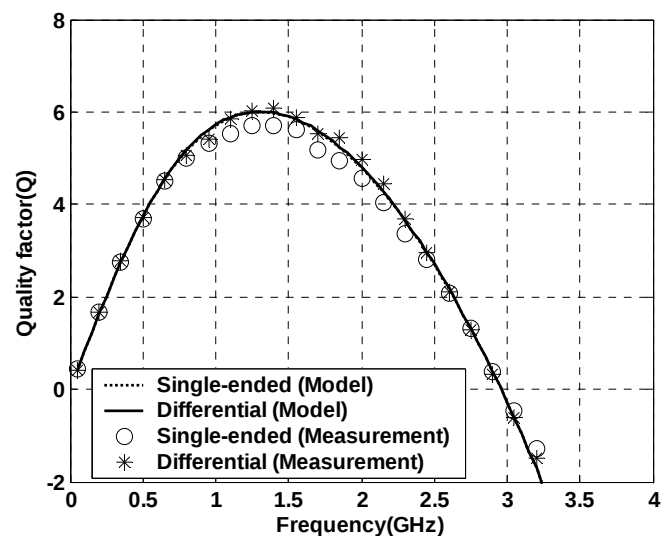
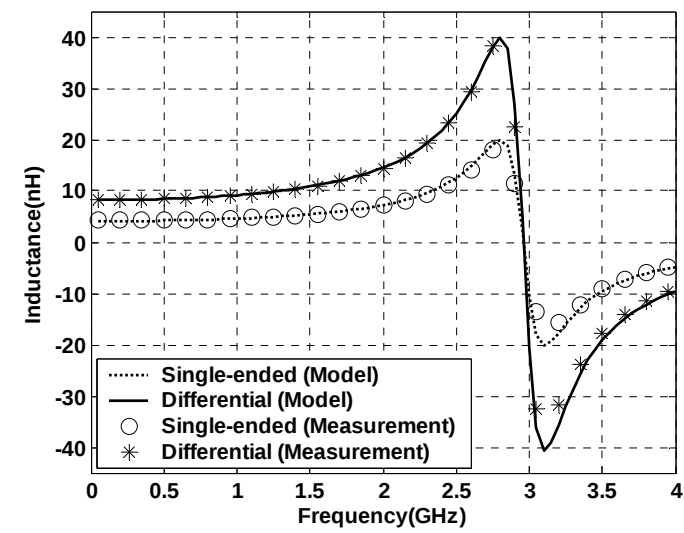
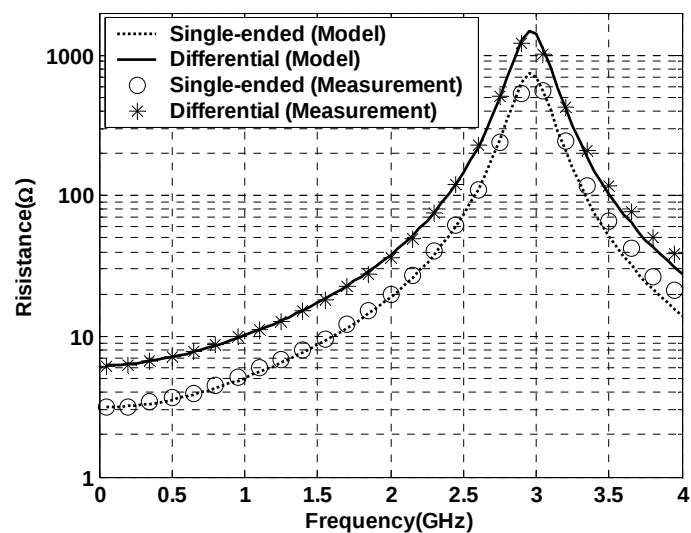
$$Q_{eff} = \frac{\operatorname{Im}[R + jX]}{\operatorname{Re}[R + jX]} = \frac{2\pi f \cdot L_{eff}}{R_{eff}}$$

中心抽头等效模型的验证

- 0.35 μm 1P4M RF Mixed-signal Process
- 第一、二层金属的并联再与第三、四层金属的并联相串联
- M1, M2和M3厚度为0.64 μm , M4厚度为0.895 μm



等效模型与测试结果的比较



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